

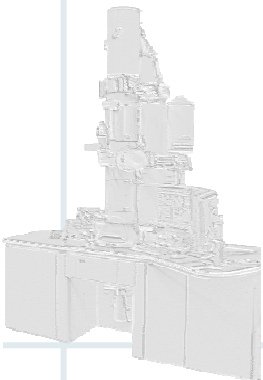
# Atomic Scale Elemental Analysis with Spherical Aberration Corrected STEM

**T. Oikawa<sup>1</sup>, E. Okunishi<sup>2</sup> and S. Kuypers<sup>3</sup>**

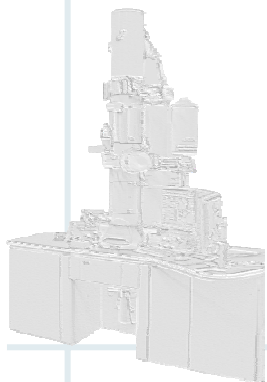
1 JEOL(Europe) SAS, 78209 Croissy-sur-Seine, France

2 JEOL Ltd, Akishima, Tokyo 196-8558, Japan

3 JEOL(Europe) BV, B-1930 ZAVENTEN, Belgium



# Why Scanning Transmission Electron Microscopy?

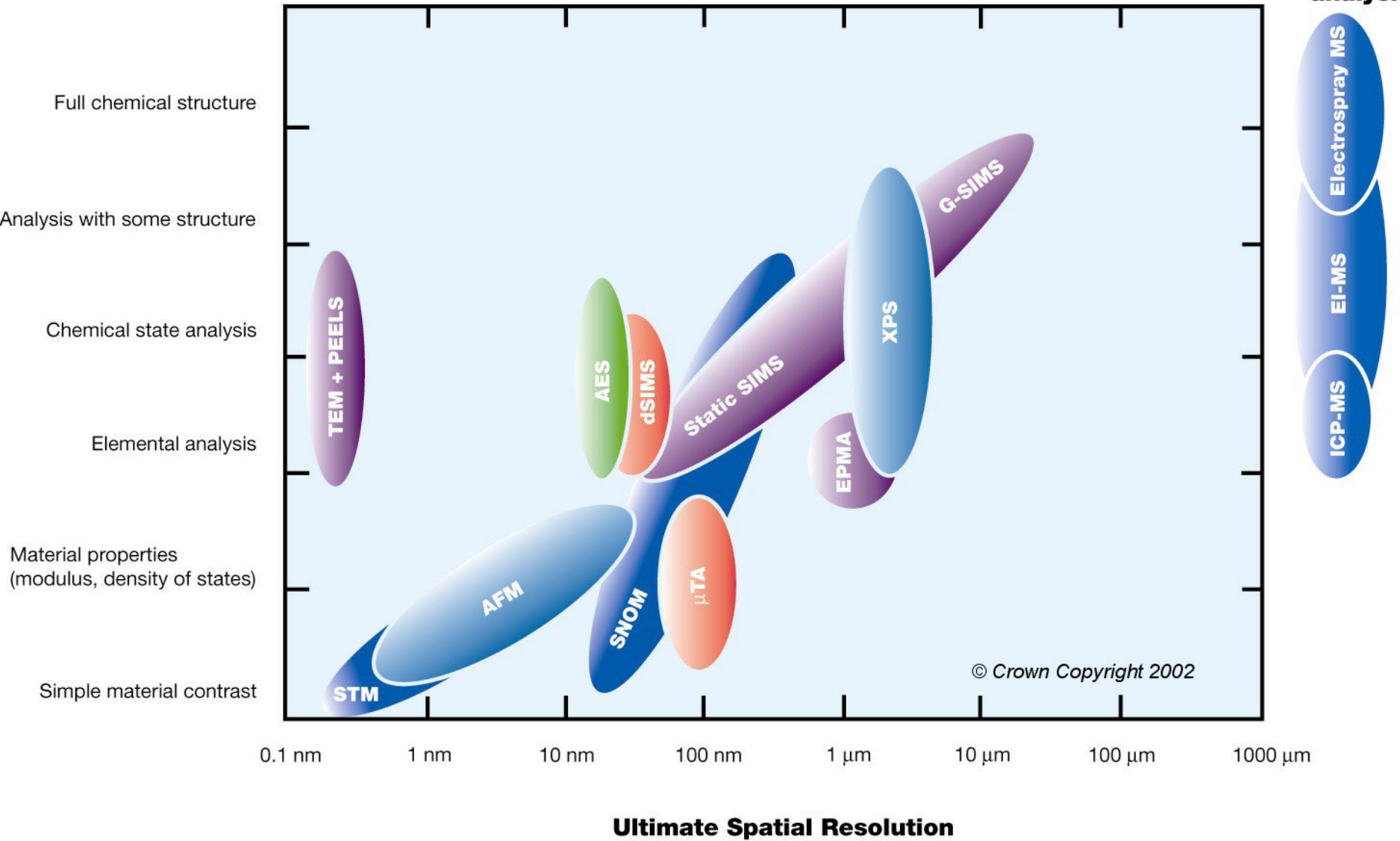


JEM-2100F with CESCOR

# Techniques for Surface and Nanoanalysis

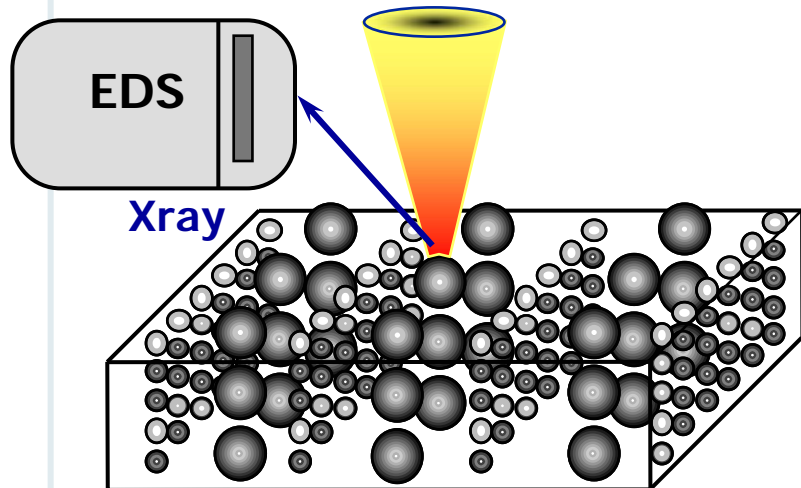
## Surface and Nanoanalysis

## Bulk analysis



# STEM is a very powerful analytical tool

Electron Probe

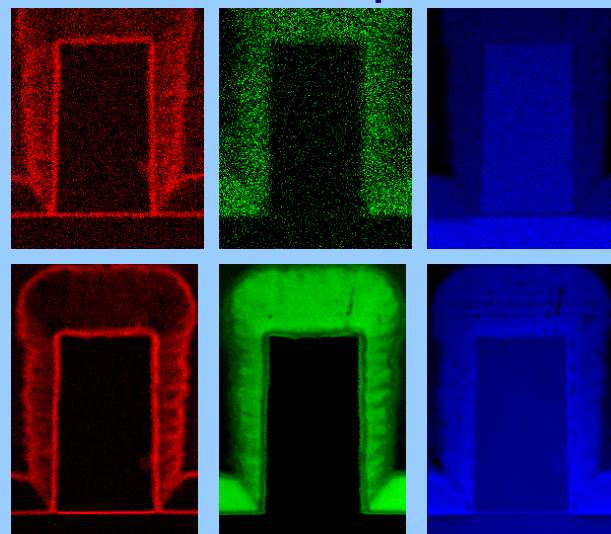
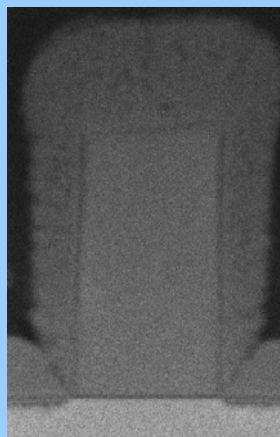


STEM uses a scanning electron probe for combined imaging and analysis

STEM image, EDS and EELS data are corrected simultaneously

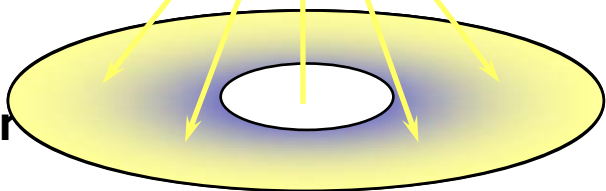
HAADF image

EDS maps



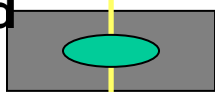
EELS maps

Scattered electrons



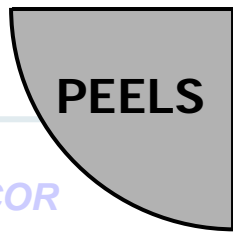
Annular Detector

Bright Field Detector



e<sup>-</sup>

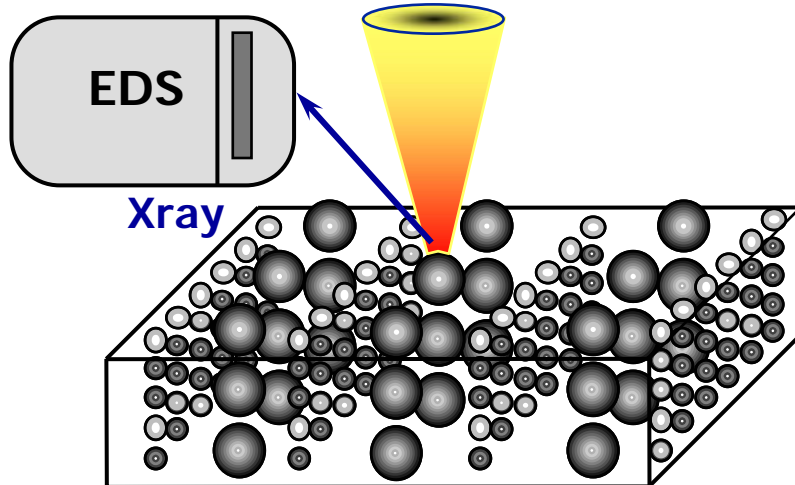
PEELS





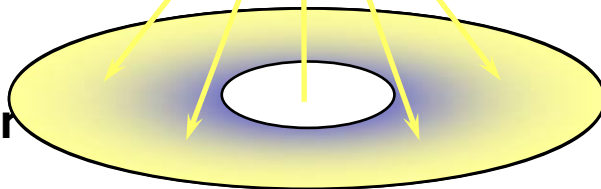
# HAADF STEM

Electron Probe



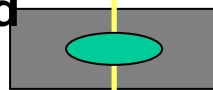
Scattered electrons

Annular Detector

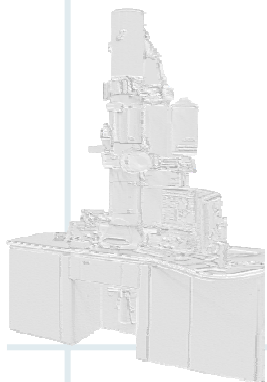
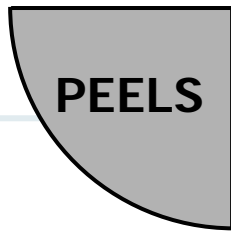


# HAADF STEM

Bright Field Detector



PEELS



Spherical Aberration corrector

CEOS  
Corrected Electron Optical  
Systems GmbH

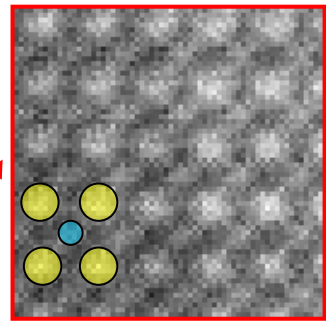
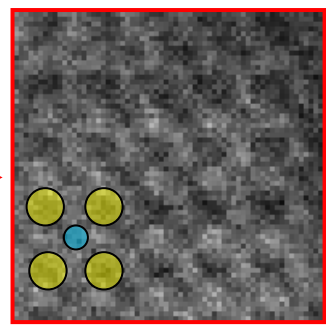
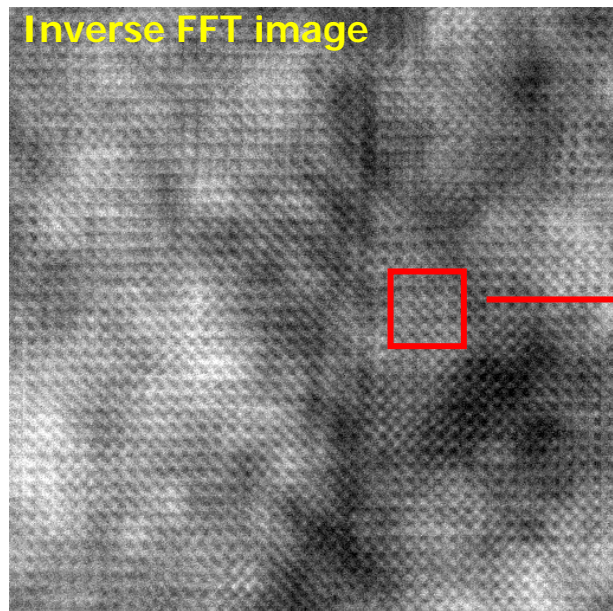
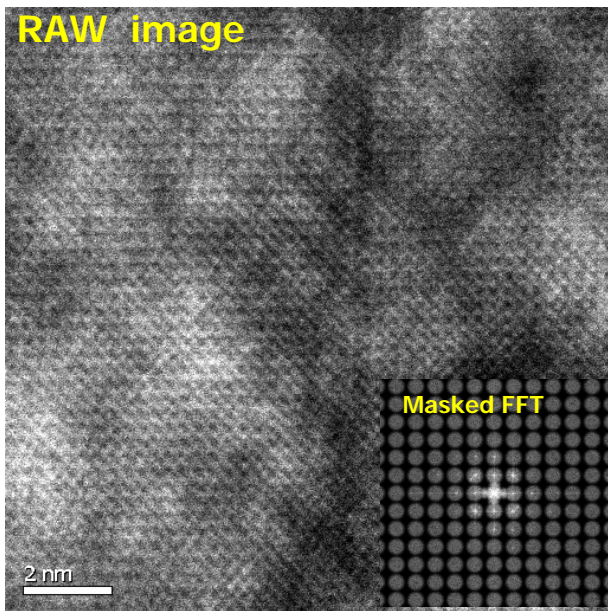


for  
Probe forming Lens

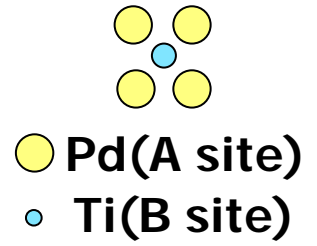
JEOL  
Serving Advanced Technology

# HR-HAADF and BF Simultaneous Image Acquisition of TiPd shape memory alloy

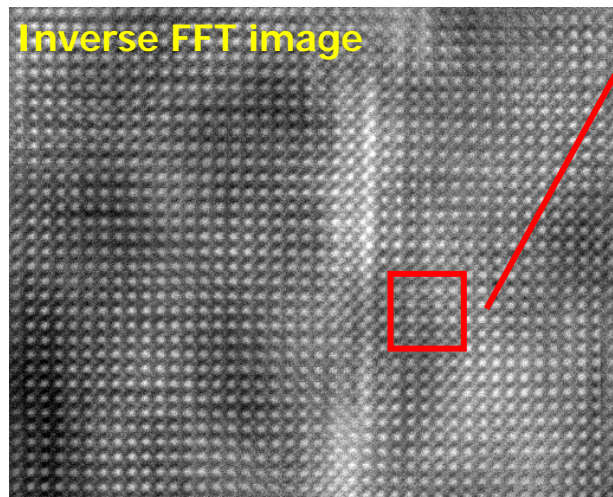
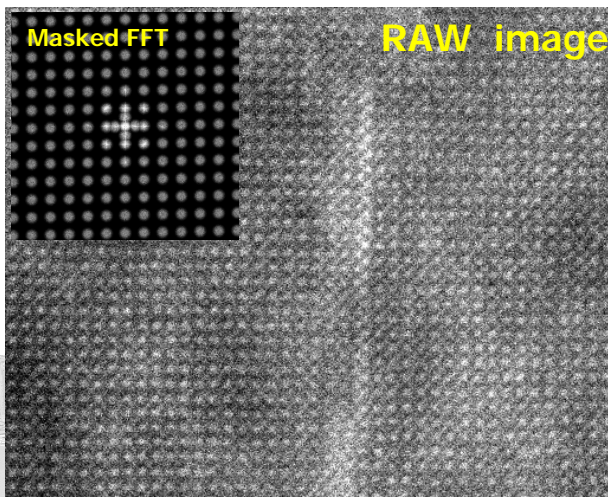
BF



Structure model



HAADF

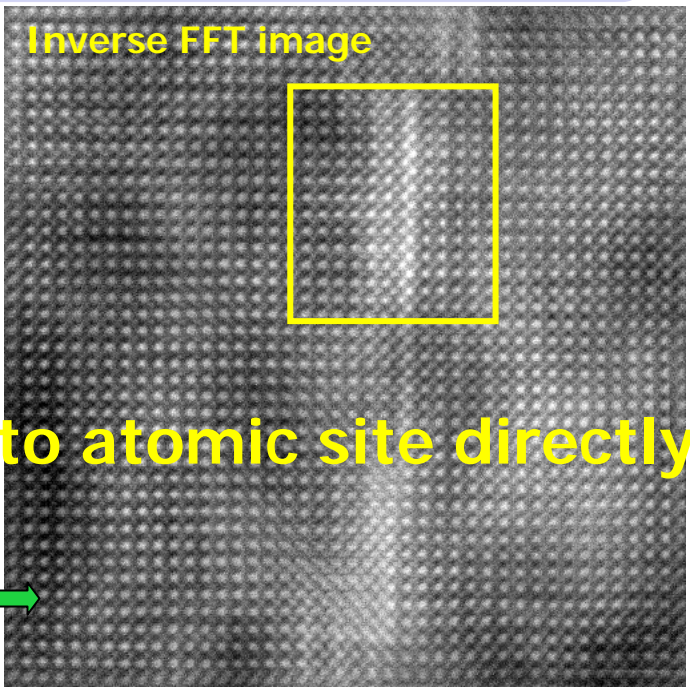
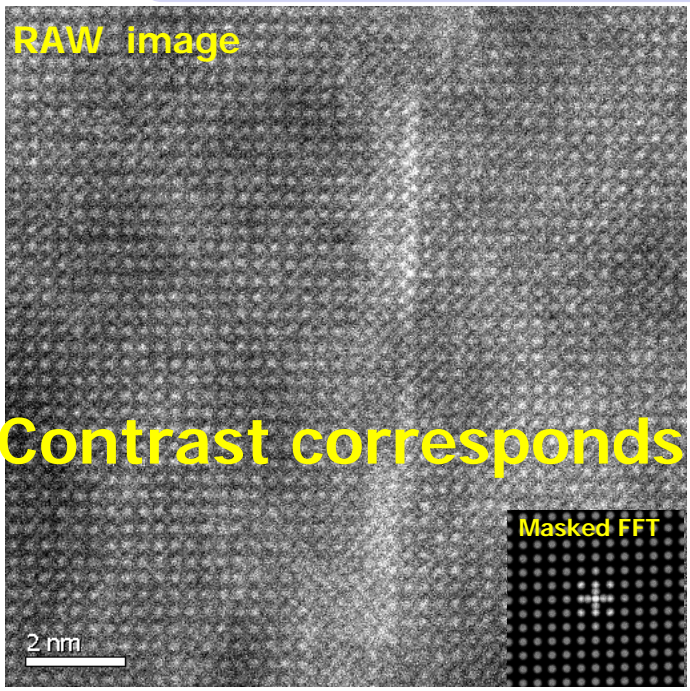


HR BF image : dark contrast corresponds to atom sites

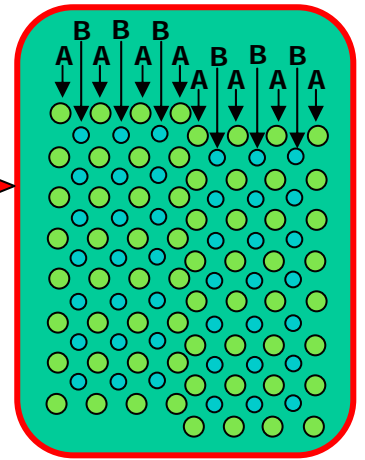
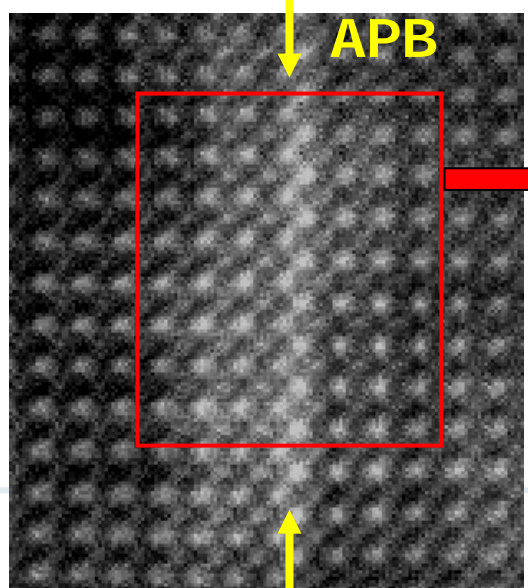
JEM-2100 HR HAADF image : bright contrast corresponds to atom sites



# HAADF image of APB(Anti Phase Boundary) in TiPd shape memory alloy

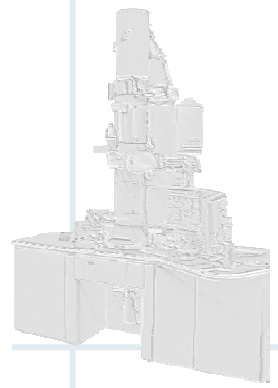


Contrast corresponds to atomic site directly

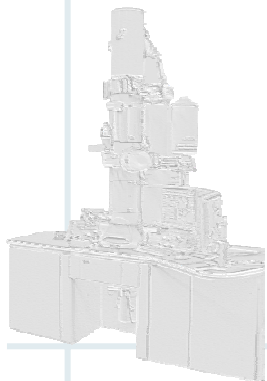


- Pd(A site)
- Ti(B site)

Data courtesy of prof . M.Nishida (Kumamoto univ)

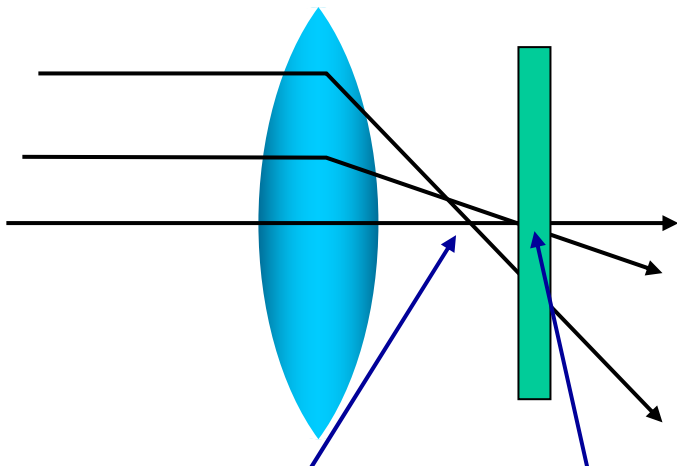


# Why correct Spherical Aberration Cs?



# Spherical Aberration Cs

## Convex lens



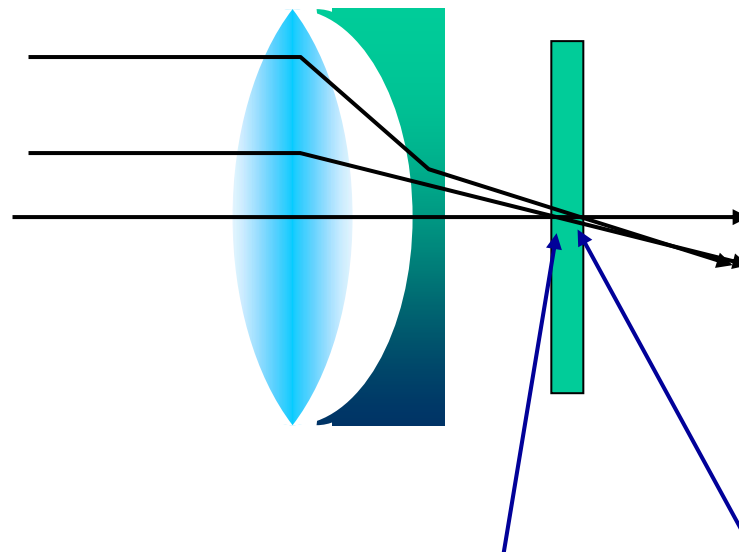
beams through the outside focus on a point outside the specimen

beams through the inside focus on a point on the specimen

Cs is not corrected

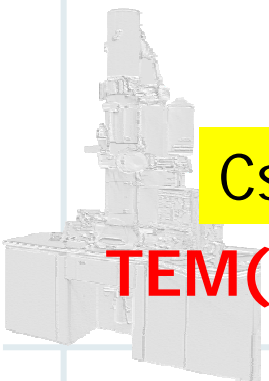
TEM (electromagnetic lens)

## Convex lens + Concave lens



beams through the inside and outside focus on the specimen

Cs is corrected



# Spherical aberration Cs

In STEM, the beam diameter on the sample is influenced by Cs.

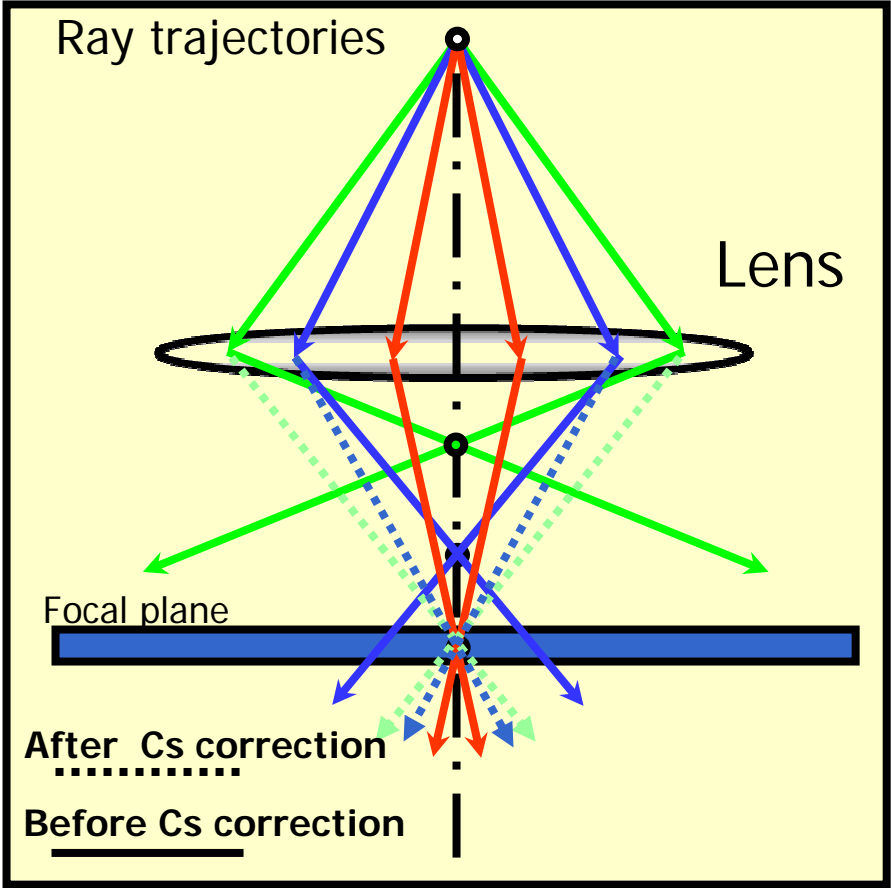
The electron beam that passed several routes is not able to focus at same point

In case of OM, optical lens:  
Cs is corrected by combination of convex lens and concave lens

In case of TEM/STEM:  
electromagnetic lens,  
only convex lens.

As a consequence: **Cs** !

Recently, Cs-correctors were developed.  
Cs-correctors are constructed by combination of multiple-pole lenses.

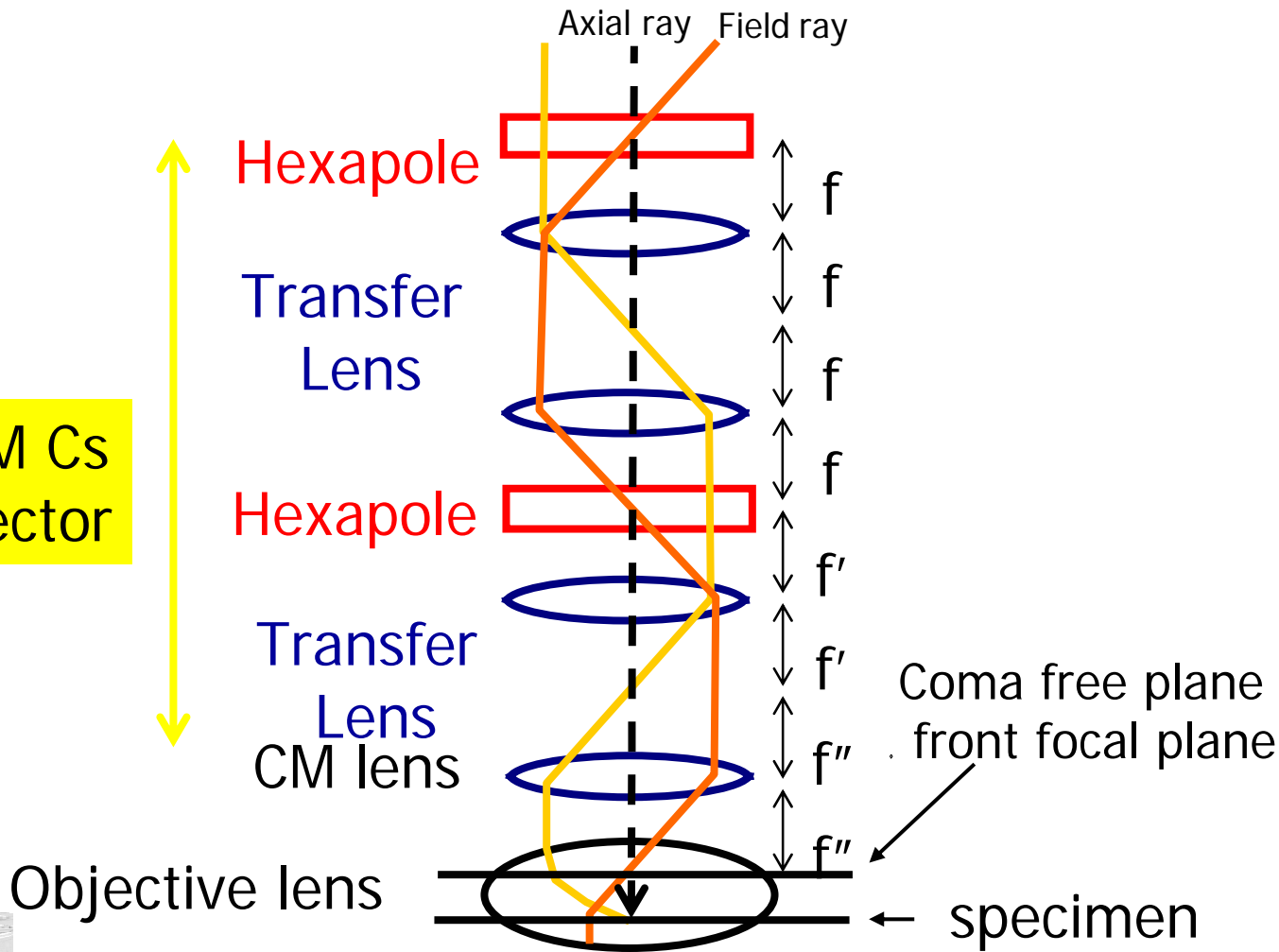
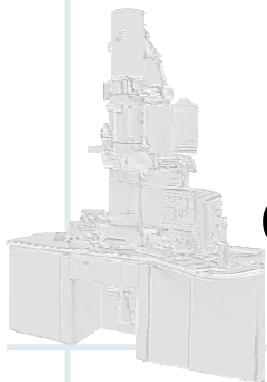


TEM/STEM performance is improved after correction of Cs

# Hexapole type Cs Corrector

M.Haider, H.Rose (CEOS GmbH)

STEM Cs corrector



Spherical Aberration corrector

CEOS  
Corrected Electron Optical  
 Systems GmbH



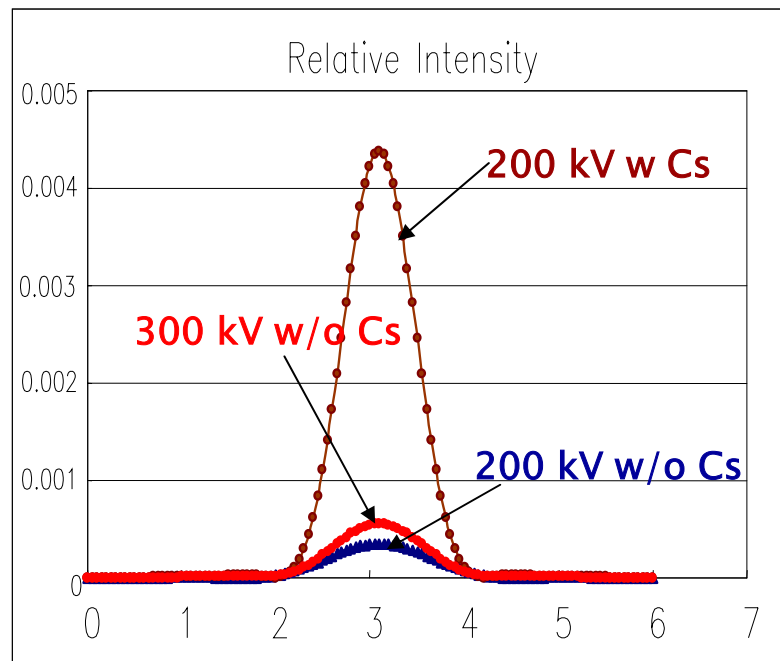
for  
 Probe forming Lens





# Effects of Cs correction for STEM

## Probe calculation



- 1 Finer probe is made: from 0.136nm to less than 0.1nm probe (FWHM)
- 2 Finer probe has higher current: from 500pA 1nm to 500pA 0.2nm probe

Cs corrector allows sub Å imaging and elemental analysis?!

# 200 kV FEG-TEM with STEM Cs corrector

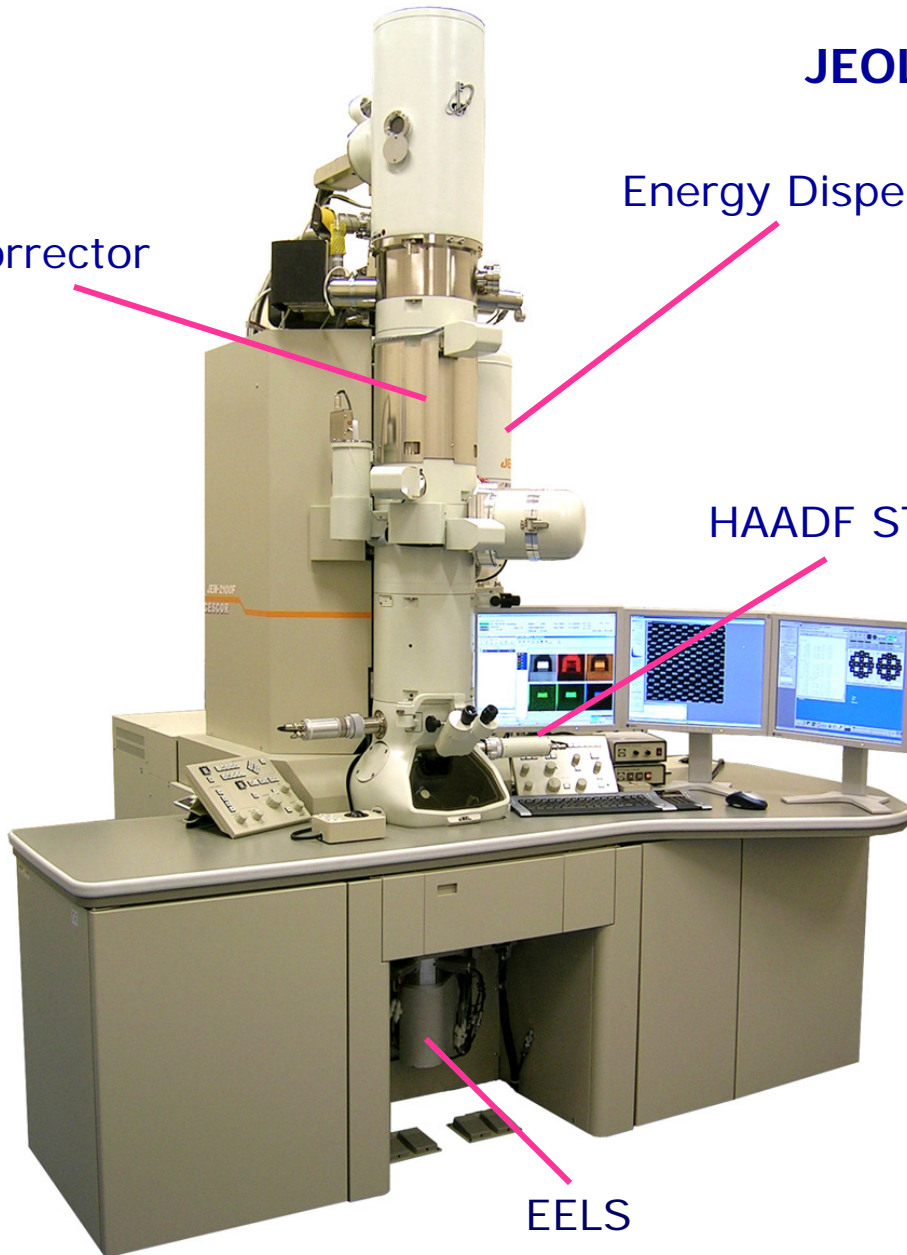
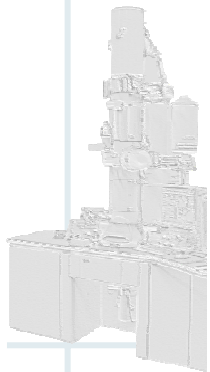
JEOL JEM-2100F Cescor

Cs Corrector

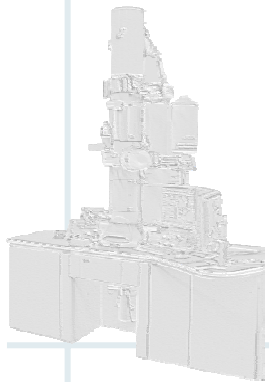
Energy Dispersive X-ray Analyzer

HAADF STEM Detector

EELS

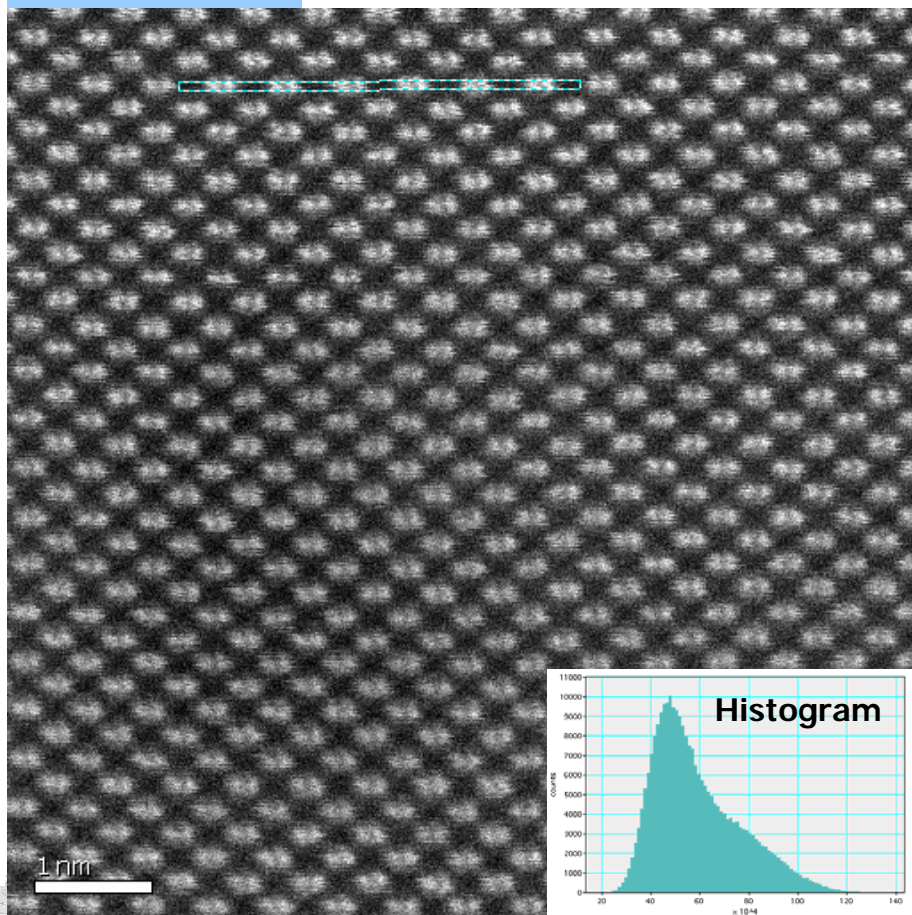


# Imaging capability of Cs corrected STEM

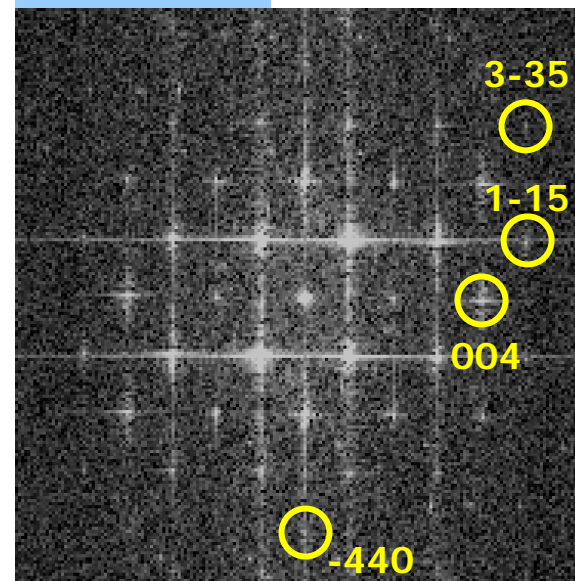


# HAADF STEM resolution) Si[110] dumbbell image

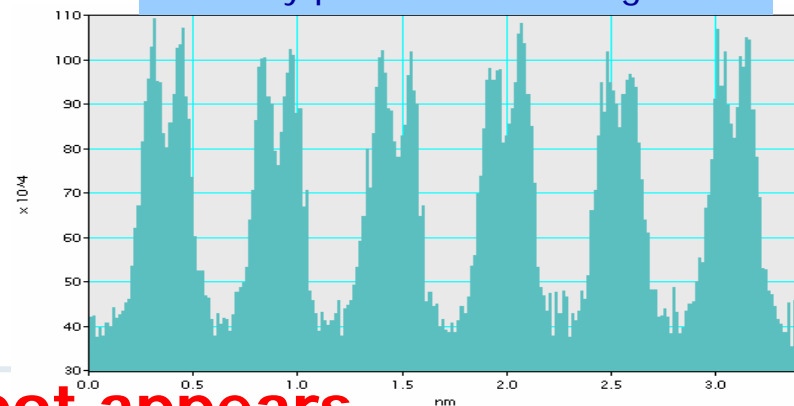
HAADF image



FFT pattern

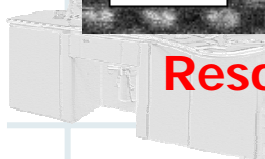


Intensity profile from rectangle area



Resolution better than 0.09nm

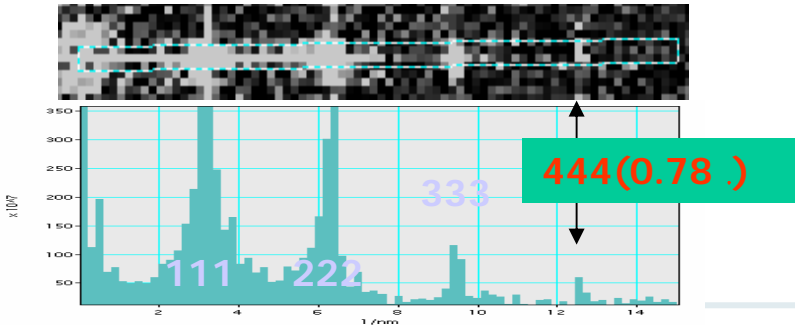
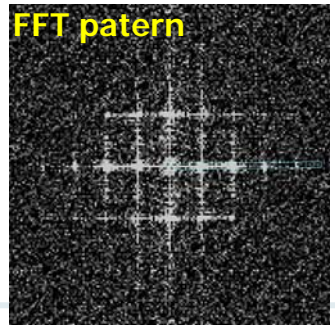
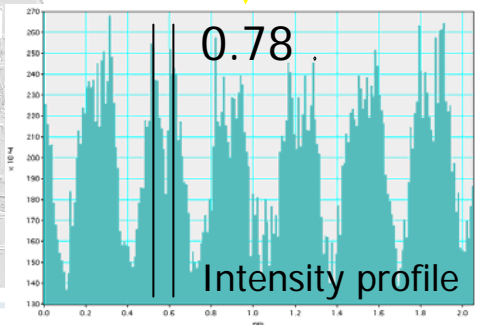
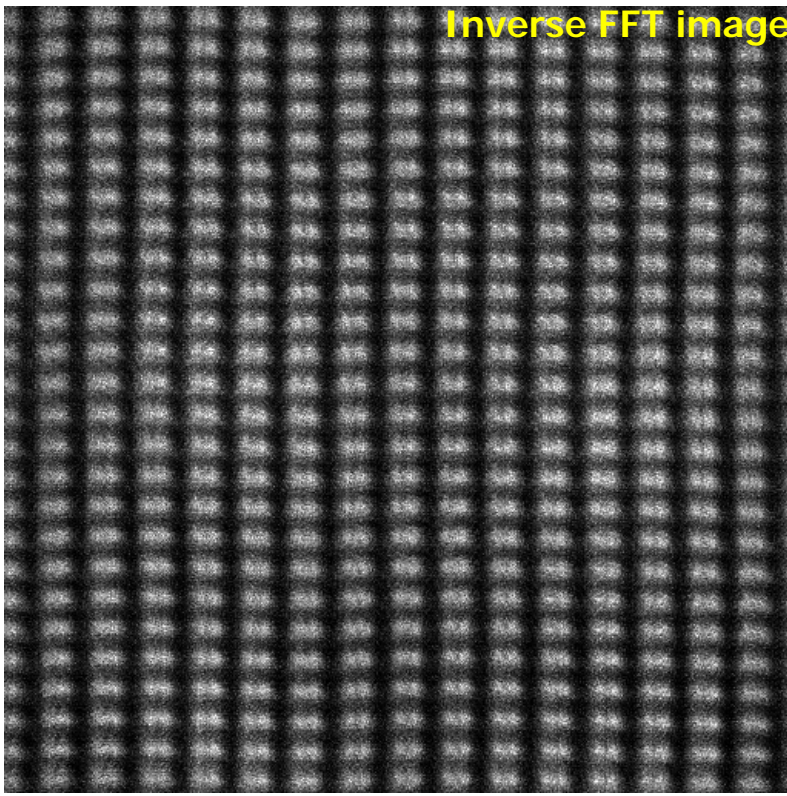
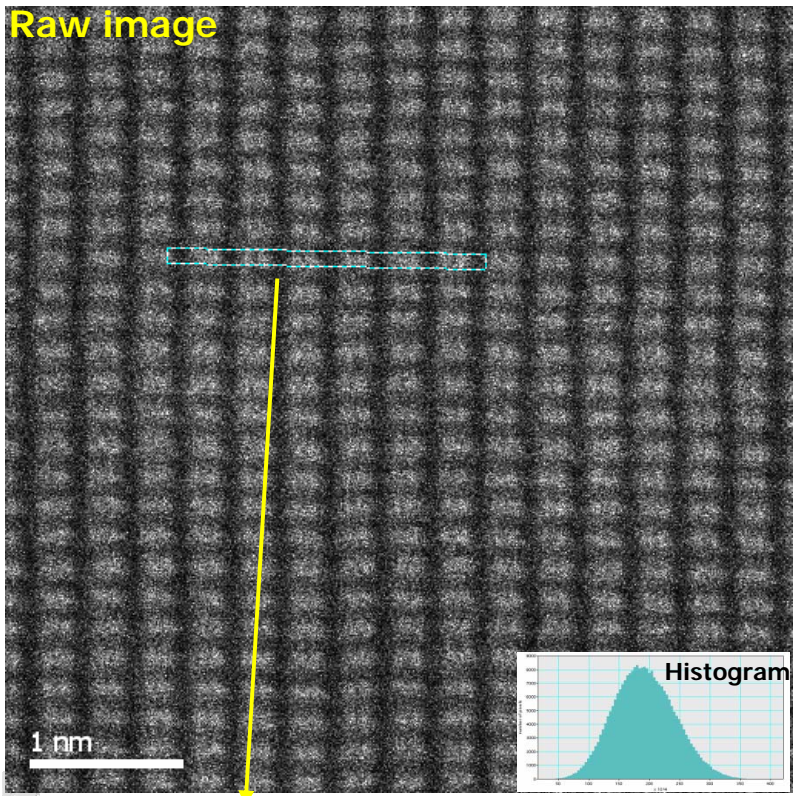
**0.083nm(335) spot appears**





# Image Resolution by Cs-corrected HAADF imaging

0.78 nm resolution by Si[112] direct observation and FFT analysis



0.078 nm from Si[112] dumbbell structure

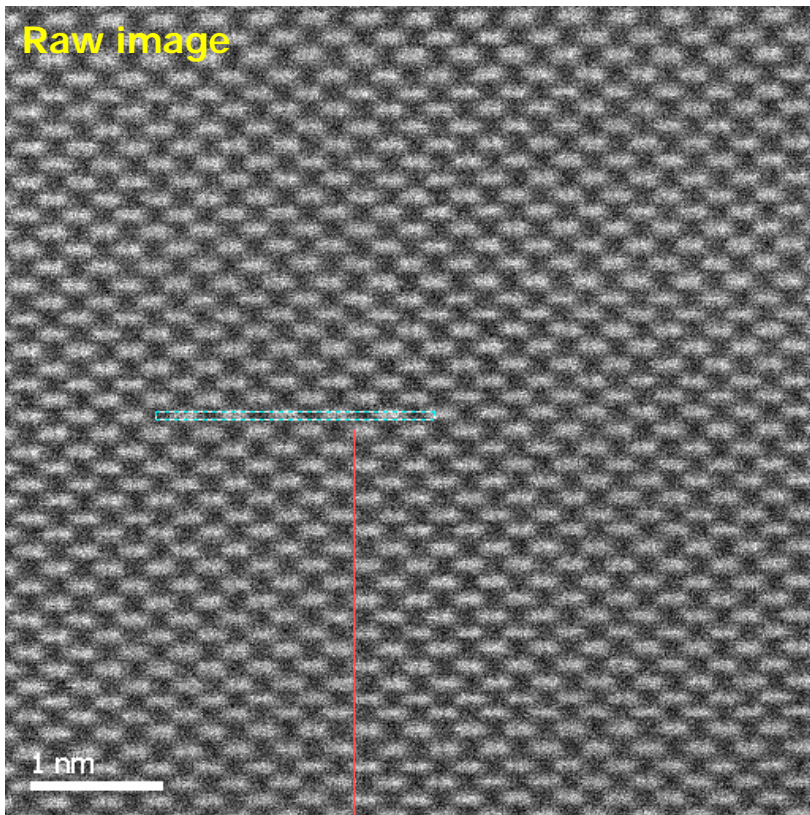
Spherical Aberration corrector  
for  
Probe forming Lens



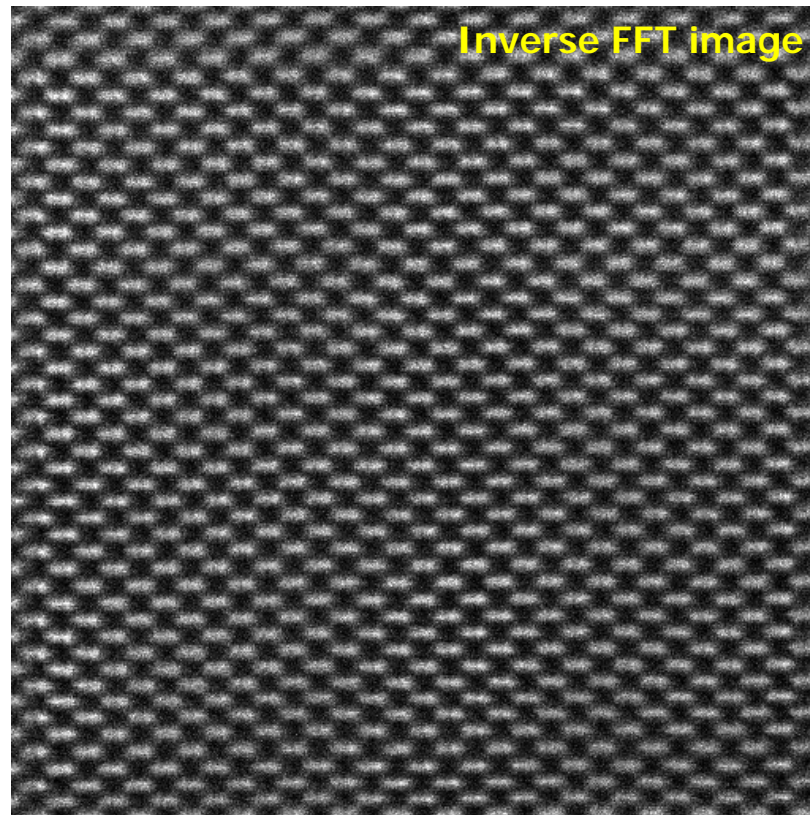


# HAADF observation of Dumbbell structure from Diamond <110>

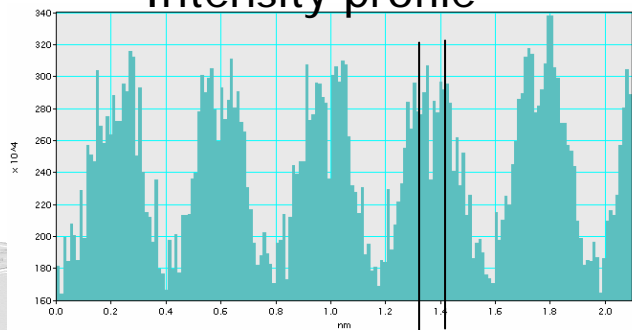
Raw image



Inverse FFT image

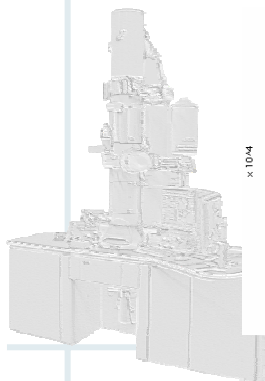
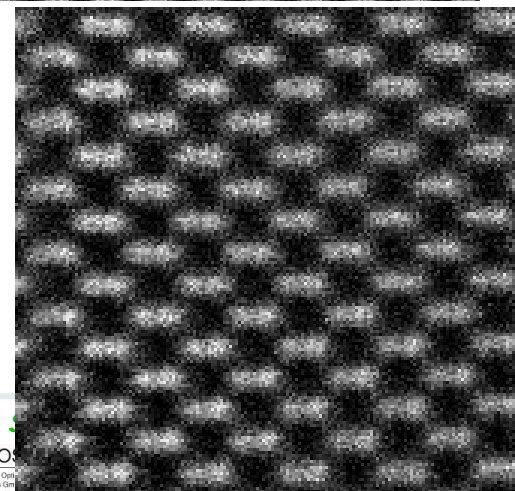
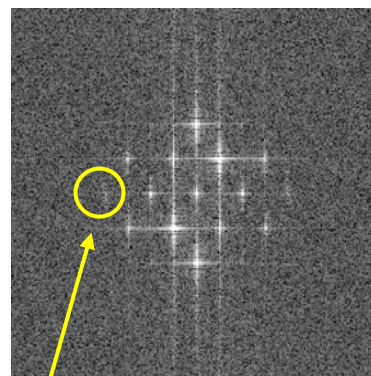


Intensity profile



0.089nm

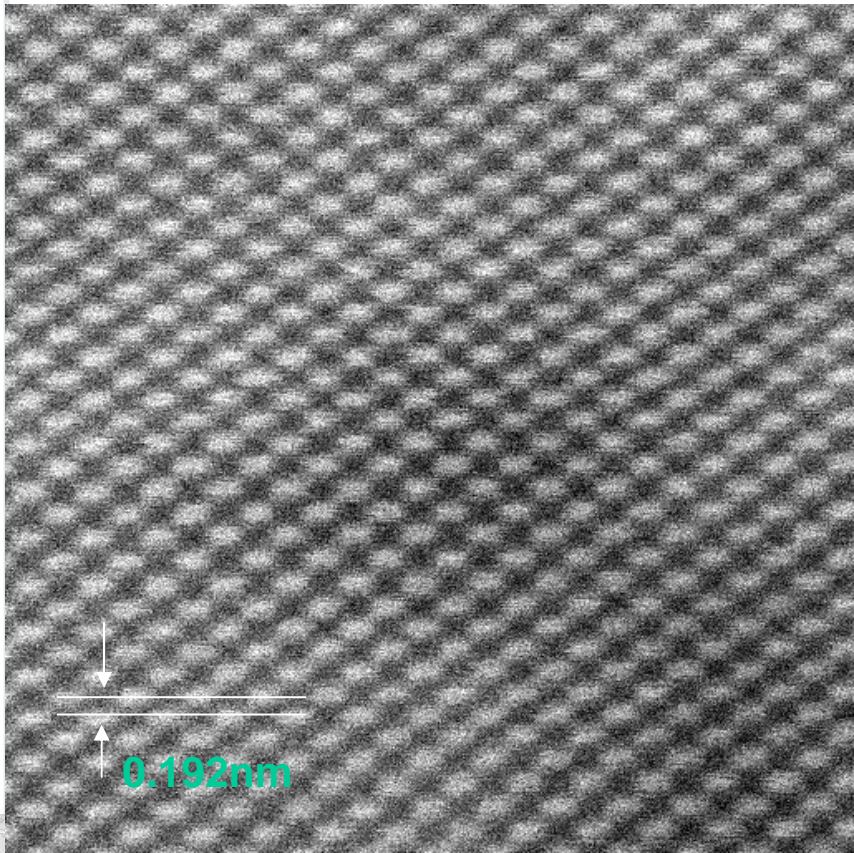
004 spot (0.089 nm)



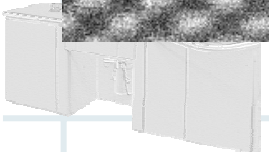
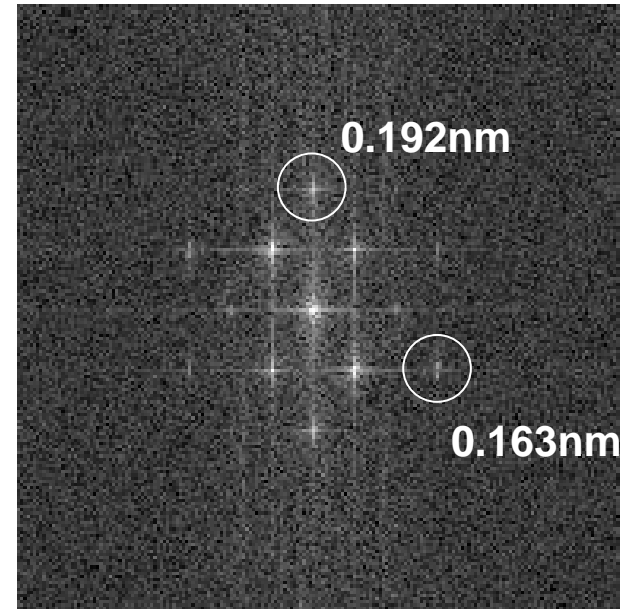
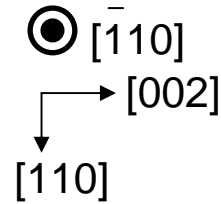


# Analytical probe size measured from FFT pattern

## HAADF image



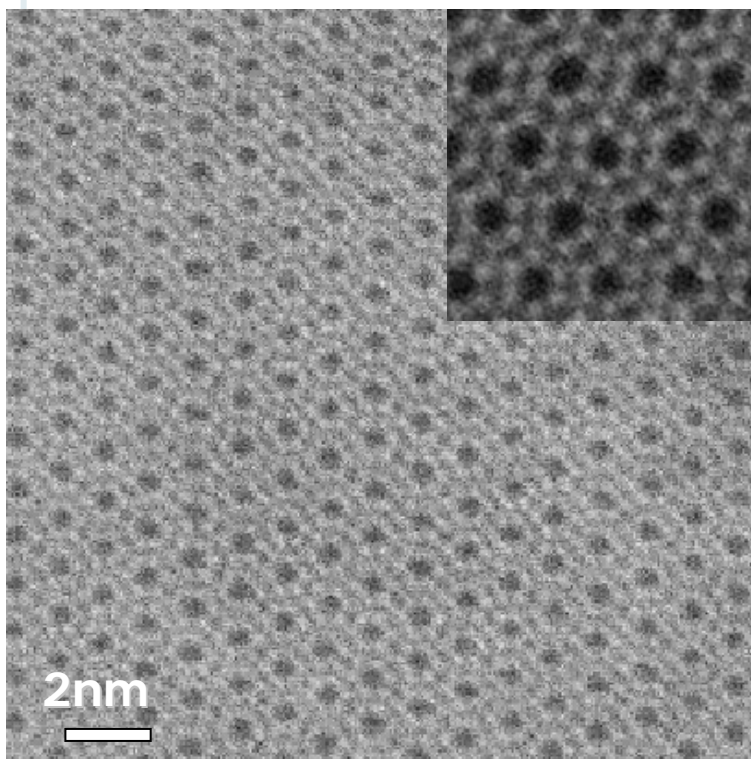
Analytical probe current : 500pA



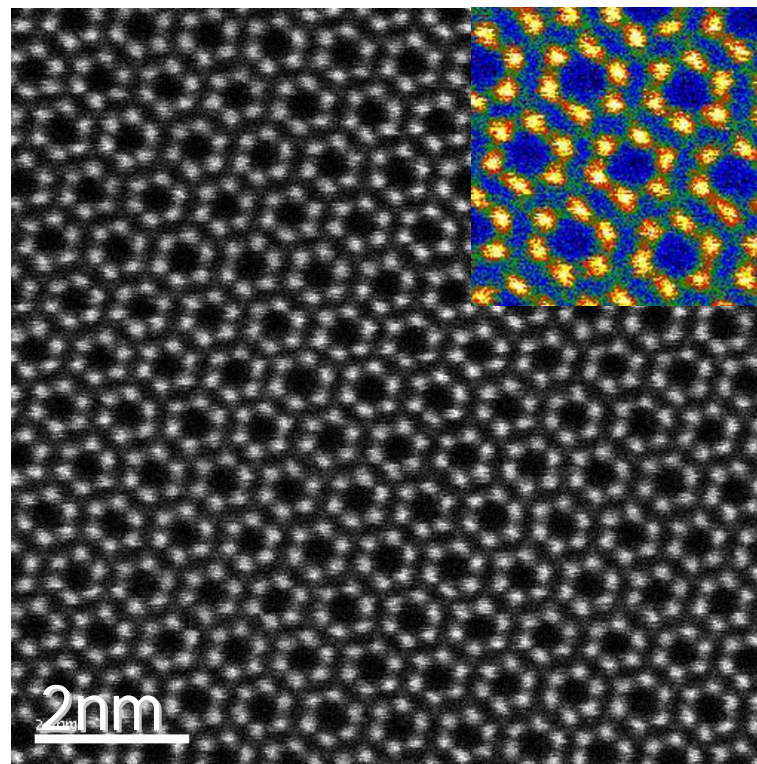


# Example: $\beta$ -Si<sub>3.4</sub>

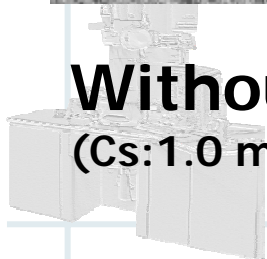
HAADF images



**Without Corrector**  
(Cs: 1.0 mm)



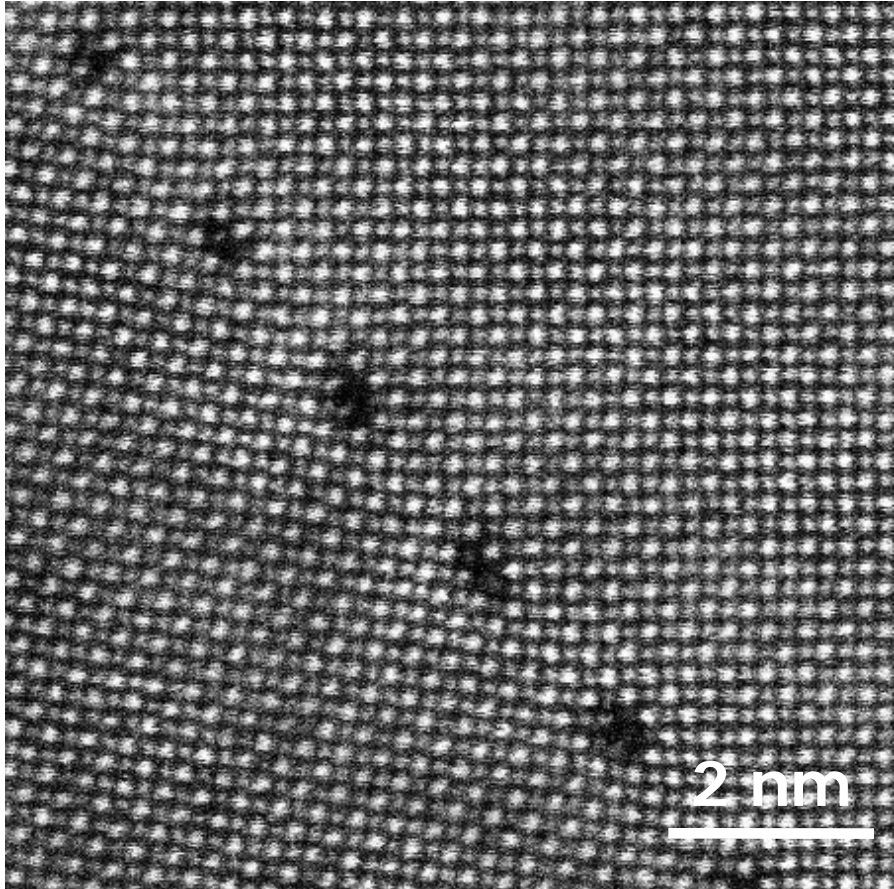
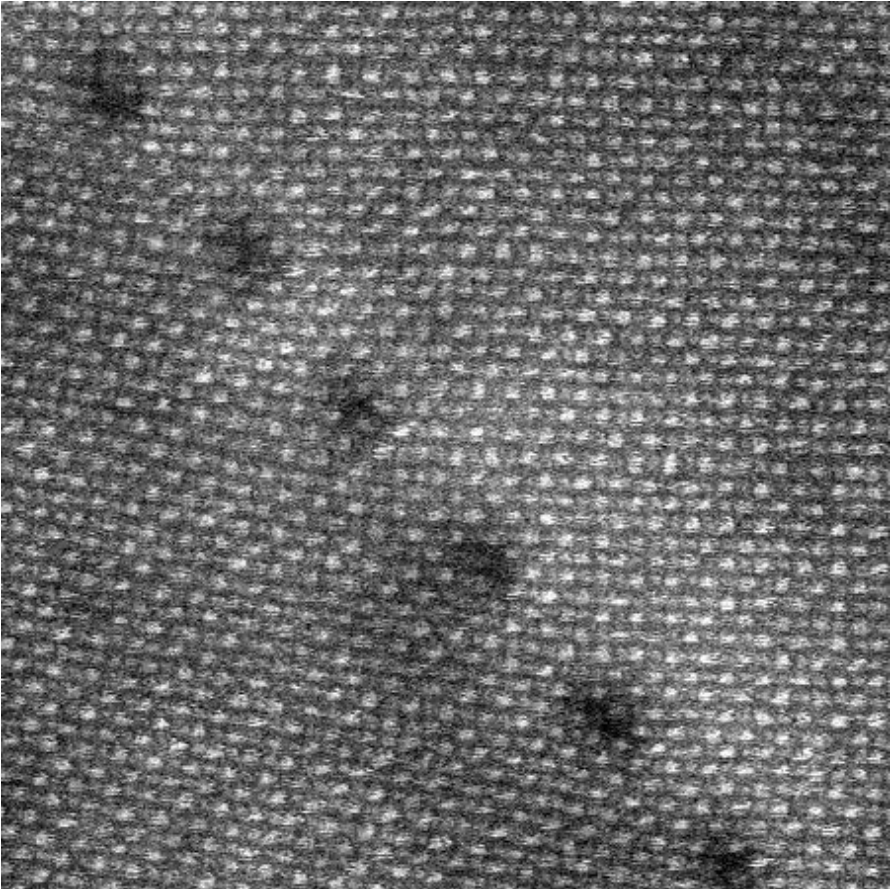
**With STEM Cs corrector**





# Example: SrTiO<sub>3</sub> Grain Boundary

HAADF images



**Without Corrector**

**With STEM Cs corrector**



Specimen: courtesy of Prof. Ikuhara/Prof. Yamamoto, The University of Tokyo

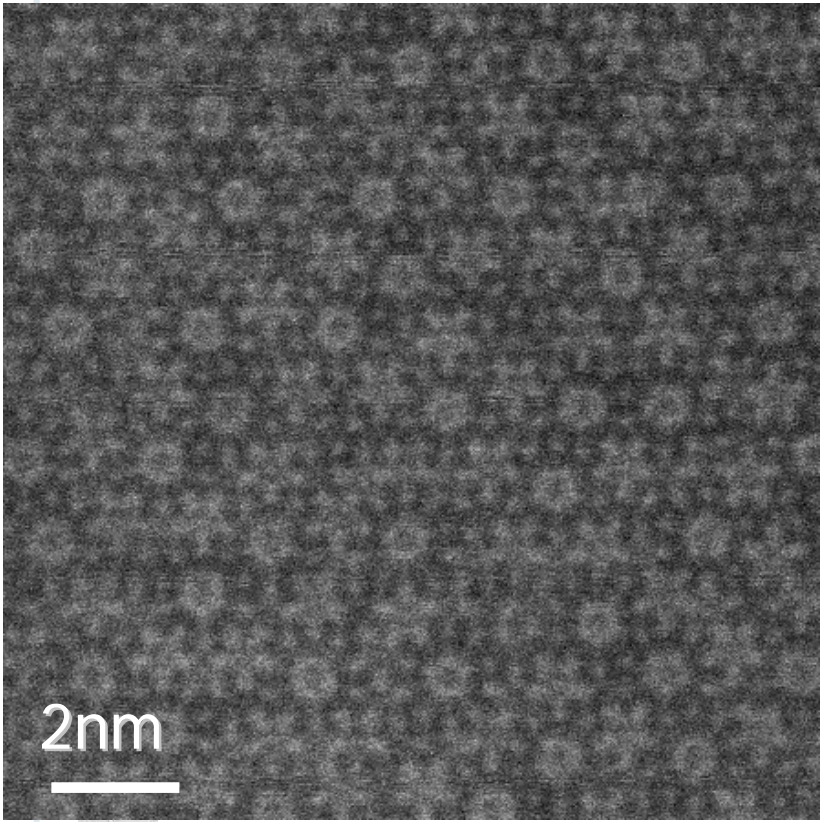
*Spherical Aberration corrector  
for  
Probe forming Lens*



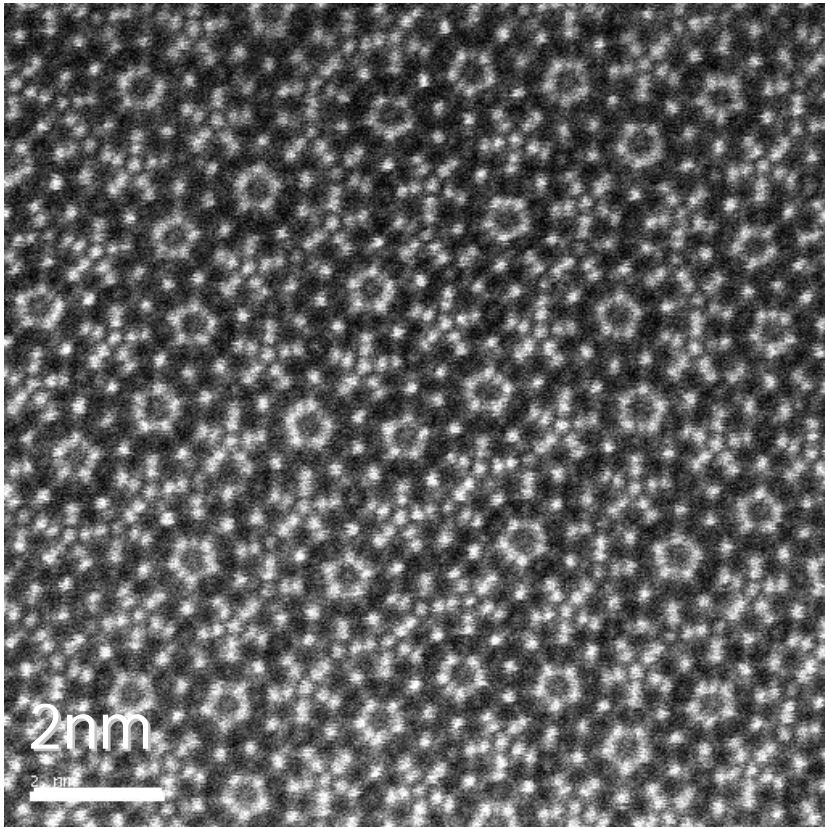


# Example: Quasicrystal (Al Cu Co)

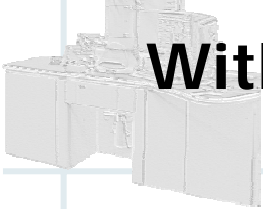
HAADF images



**Without Corrector**



**With STEM Cs corrector**



Specimen: courtesy of Prof. Eiji Abe,  
The University of Tokyo

*Spherical Aberration corrector*  
for  
*Probe forming Lens*

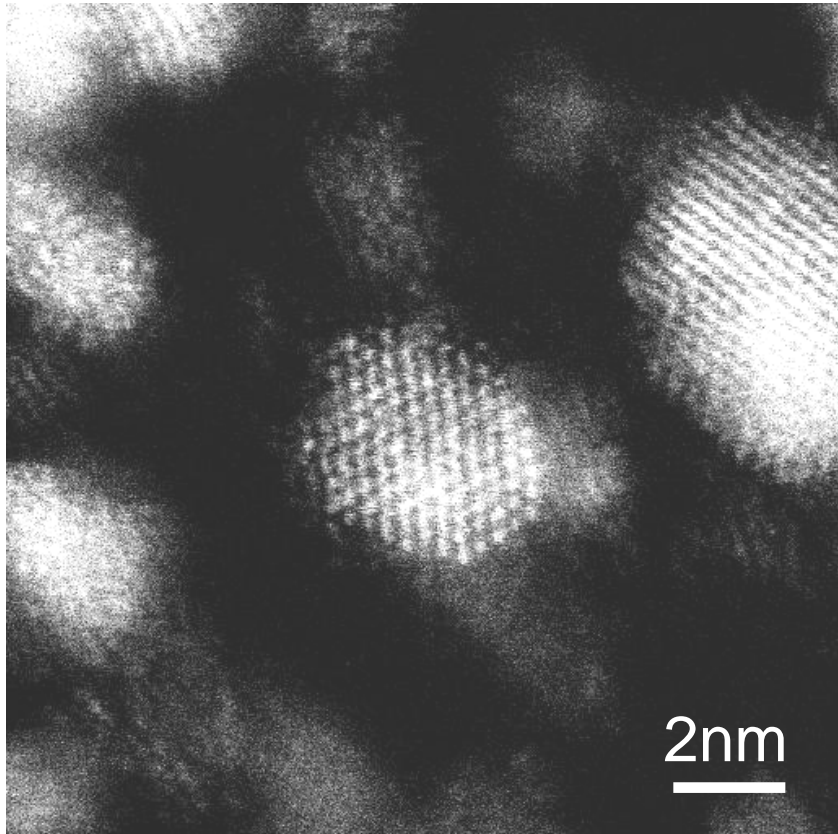
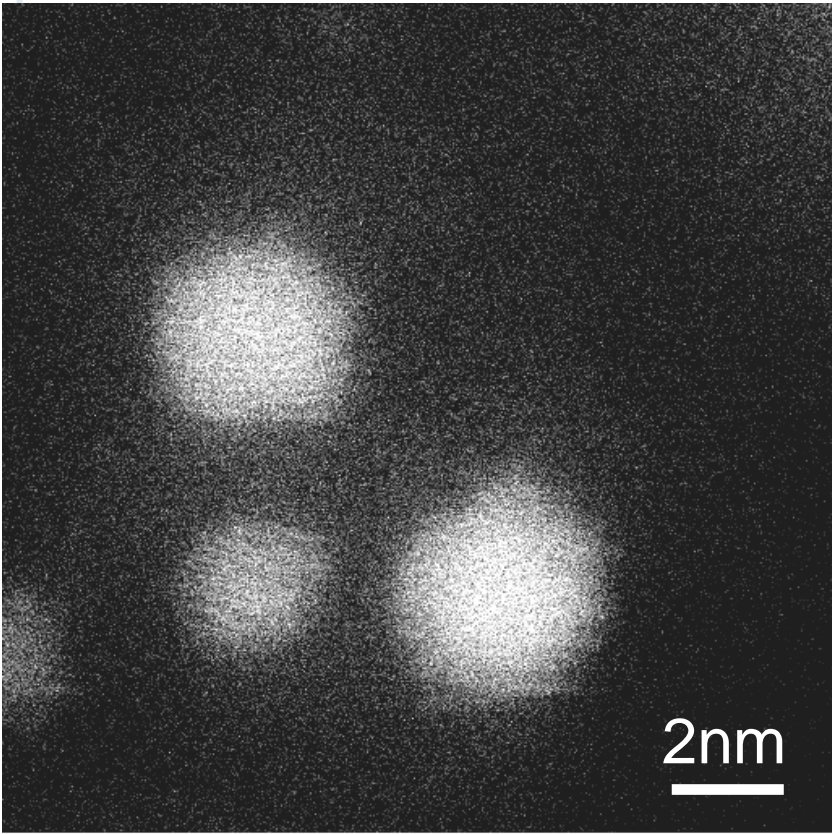
CEOS  
Corrected Electron Optical  
Systems GmbH



**JEOL**  
Serving Advanced Technology

# Example: Catalyst Pt particles

HAADF images

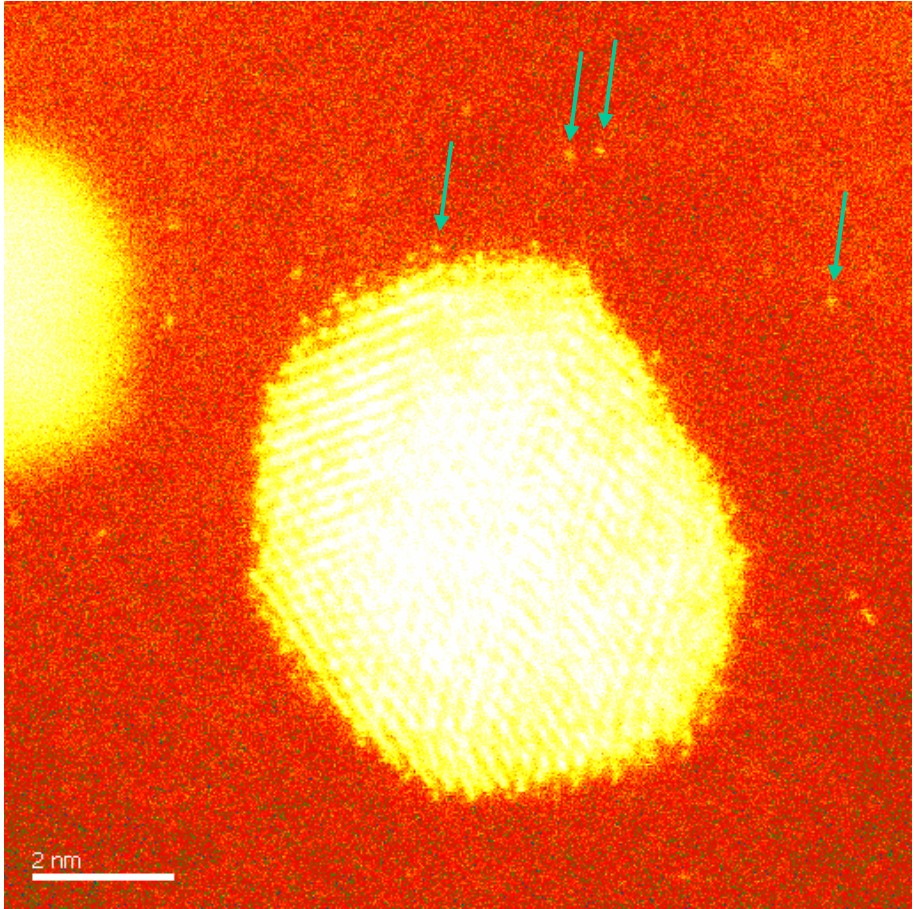
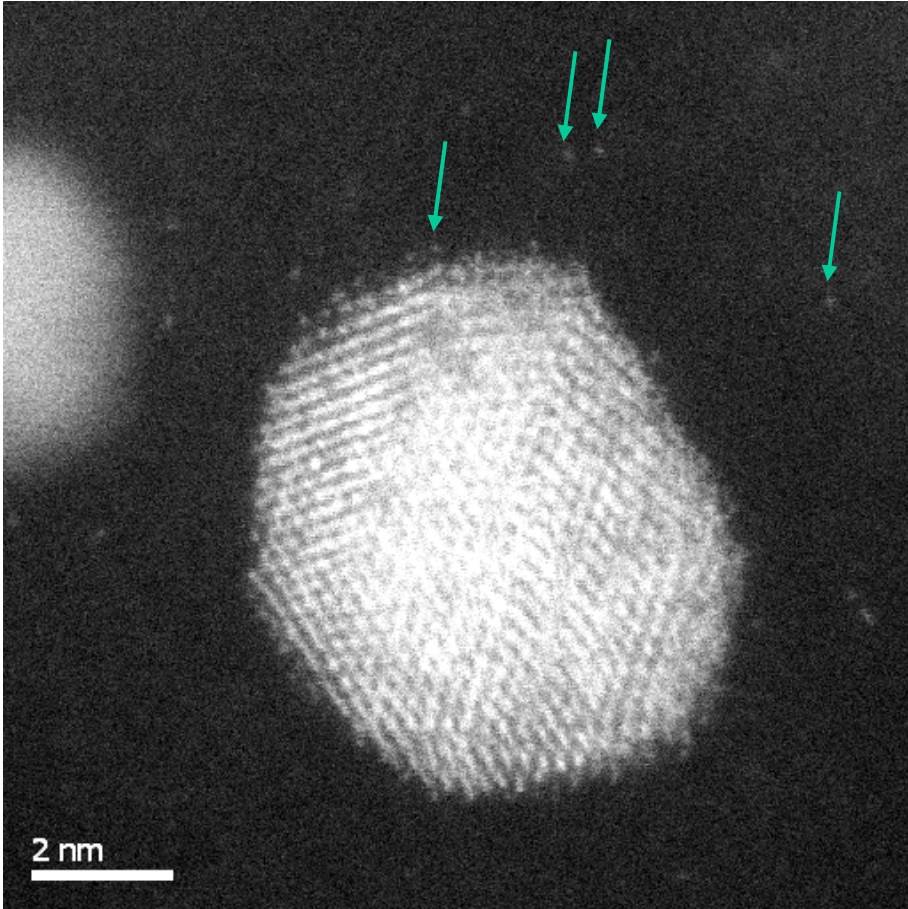


**Without Corrector**  
(Cs: 1.0 mm)

**With Cs corrector**



# Single atom observation in Pt-C

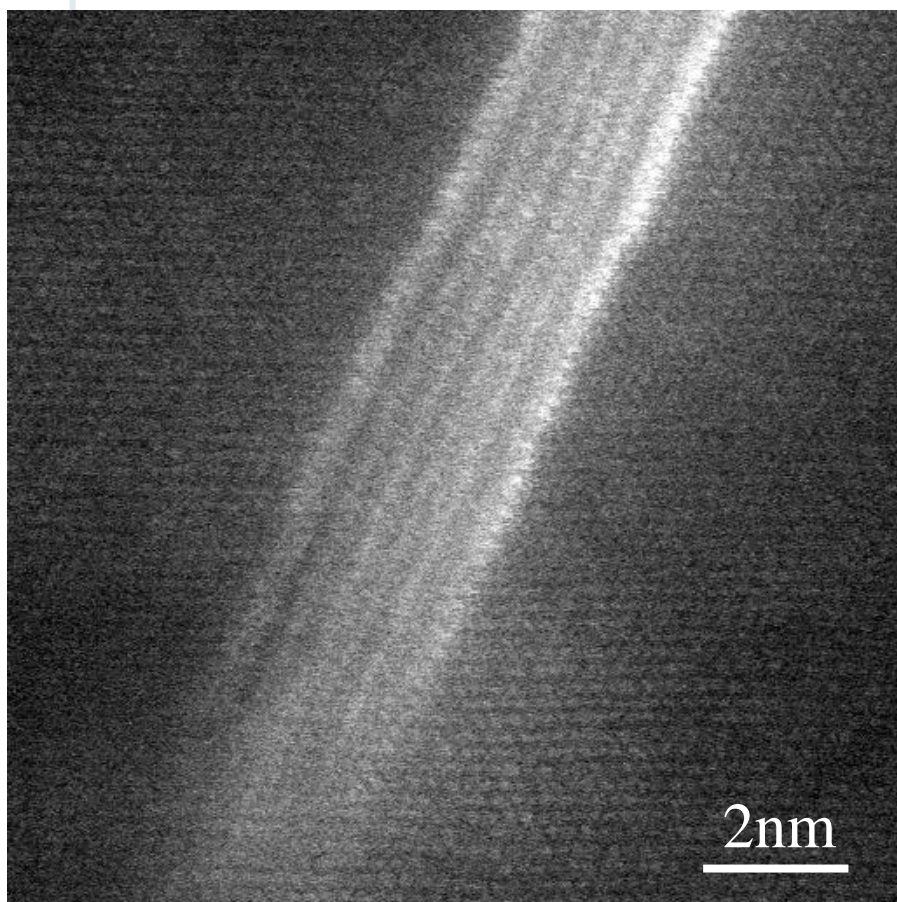


Single Pt atoms can be observed very clearly

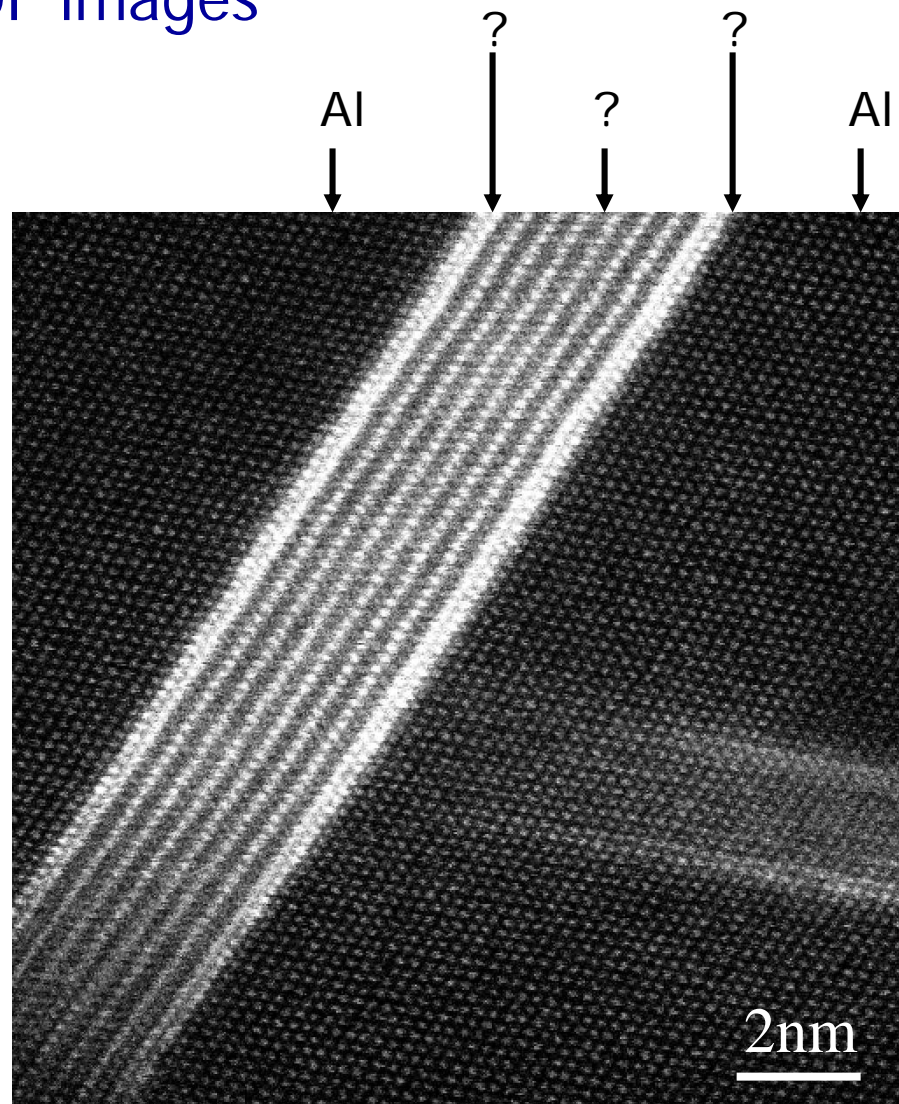


# Example: Precipitate in Al-Cu alloy

HAADF images

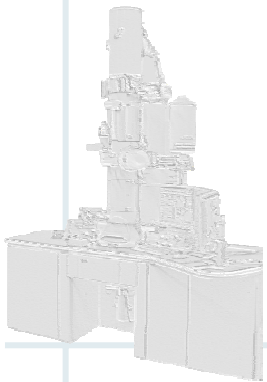


Without corrector



With Cs spherical aberration corrector

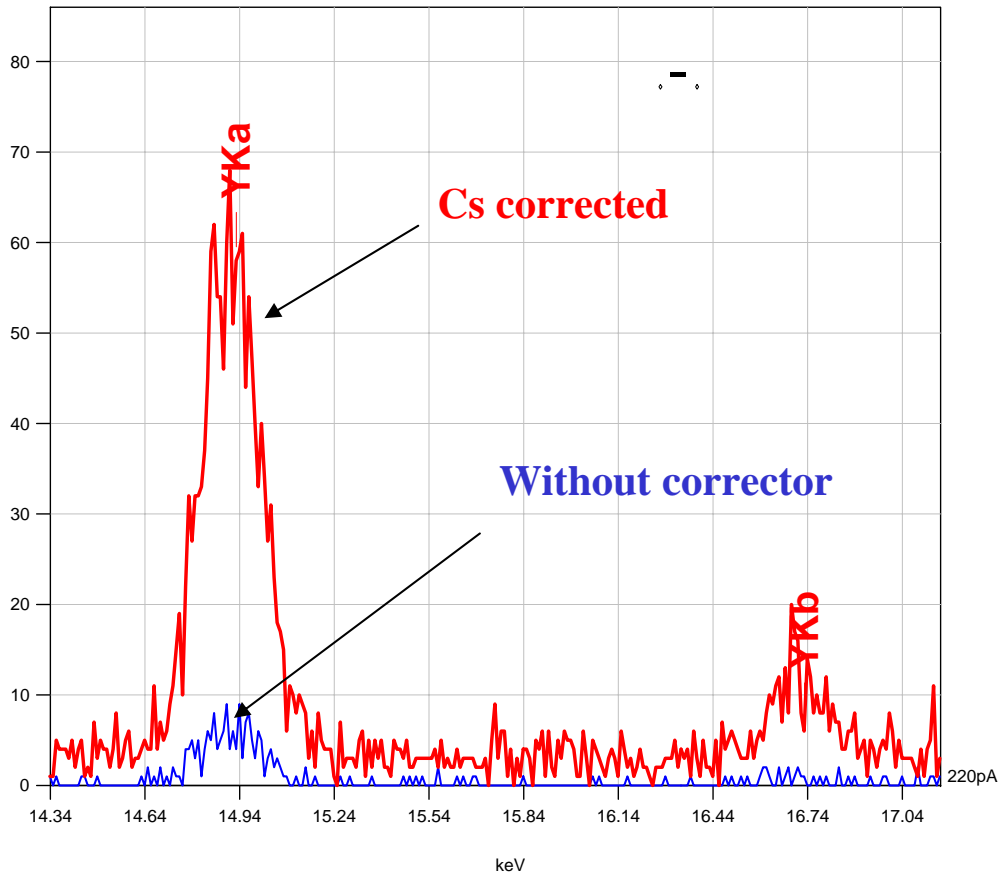
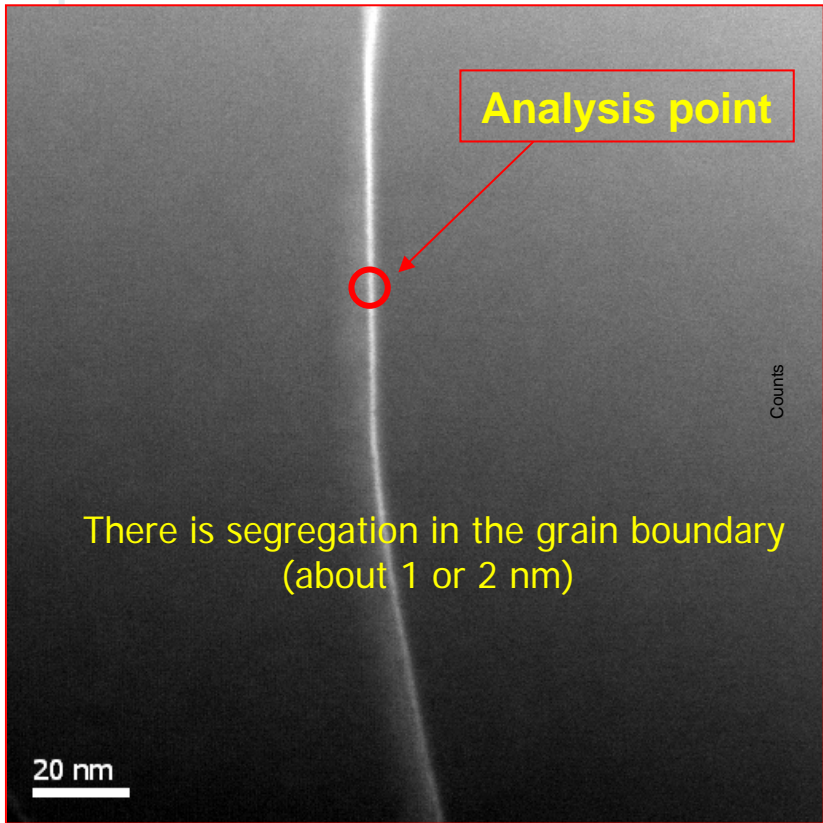
# Elemental analysis capability of Cs corrected STEM



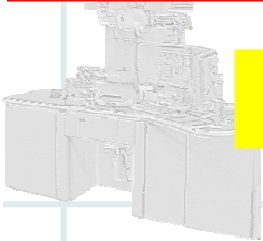


# Comparison of EDS spectra (Y-Kα)

0.5nm probe  
30s acquisition

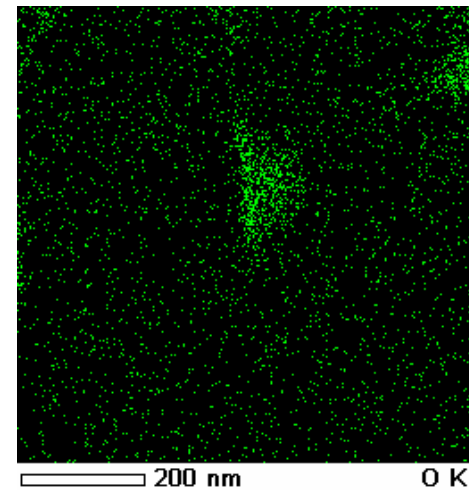
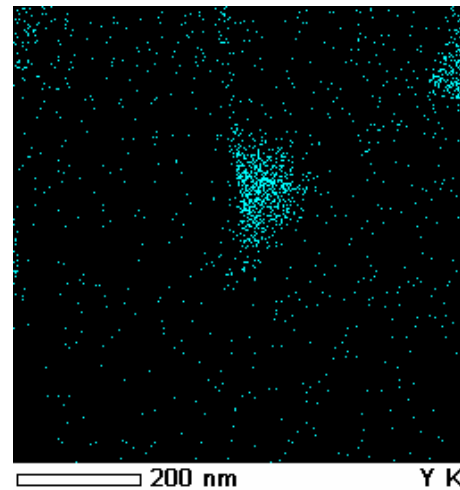
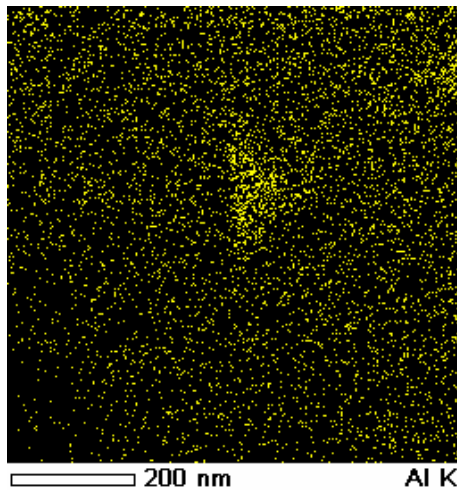
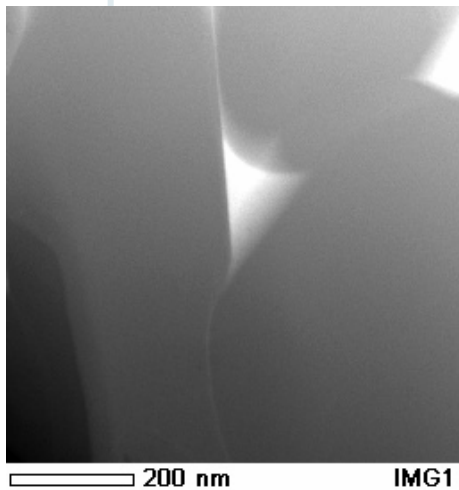


EDS signal is 6 times higher with Cs corrector

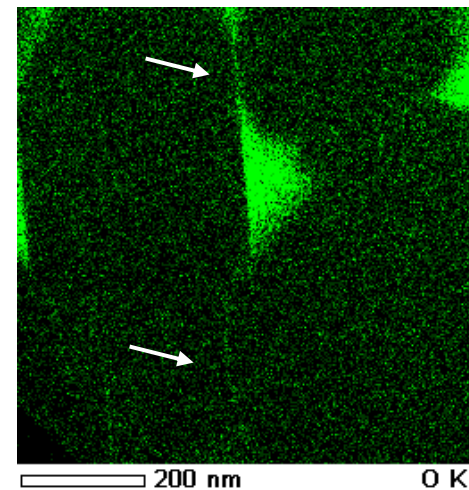
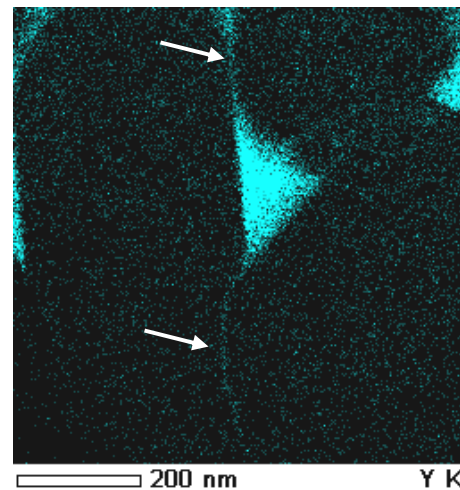
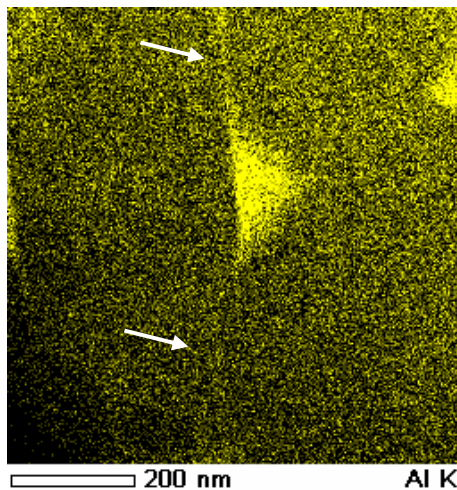
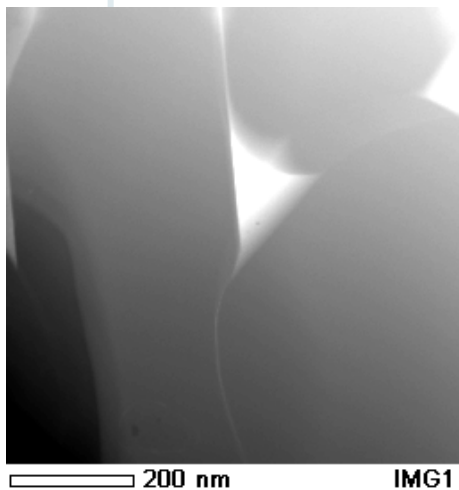


## EDS mapping of segregated elements (Al,Y,O)

## No Cs correction



## Cs correction

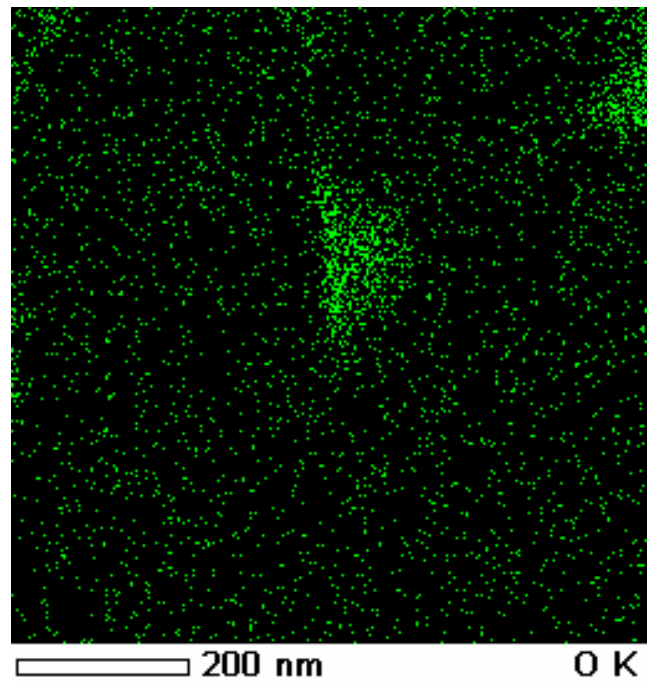
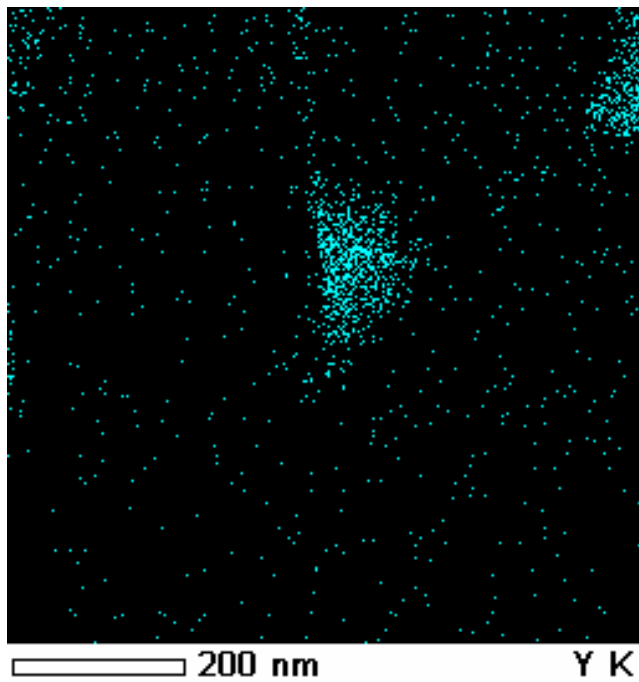


0.5nm probe  
256x256 pixels  
11 min acquisition

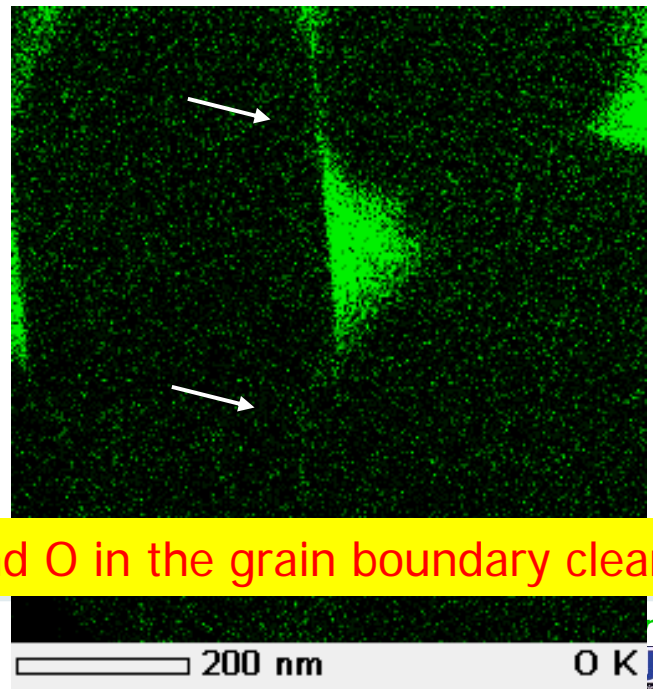
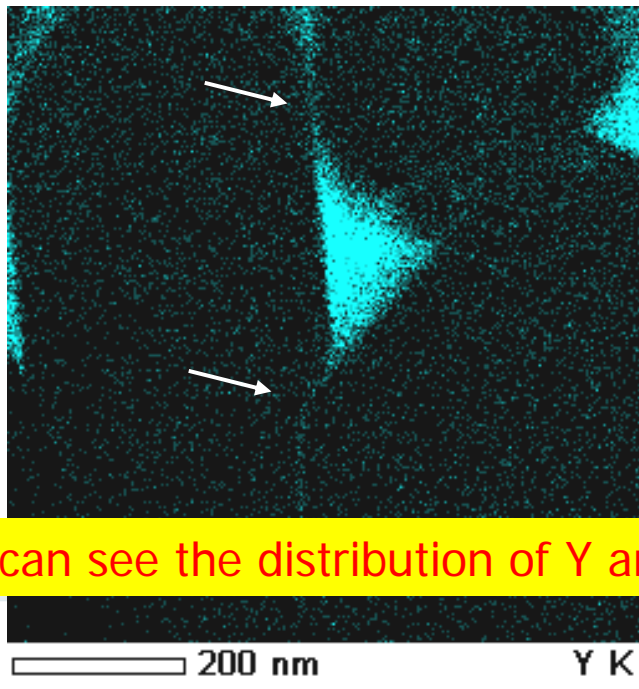
STEM image is same, but EDS map is quite different.

Good S/N ratio

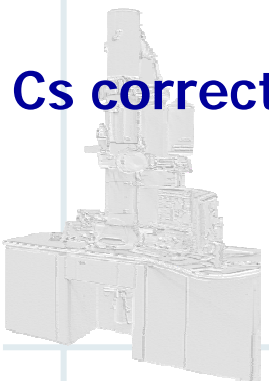
# No Cs correction



# Cs correction

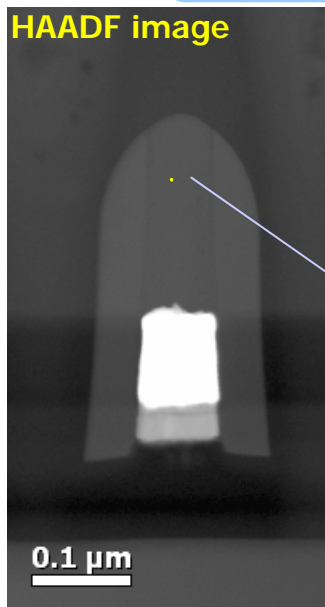


We can see the distribution of Y and O in the grain boundary clearly

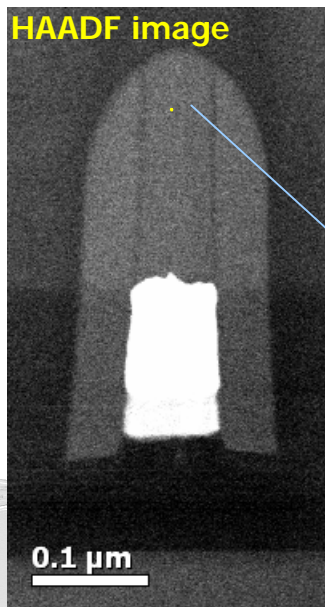


# EELS on semiconductor device

With Cs corrected



Without Cs corrected

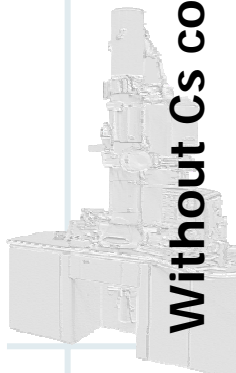
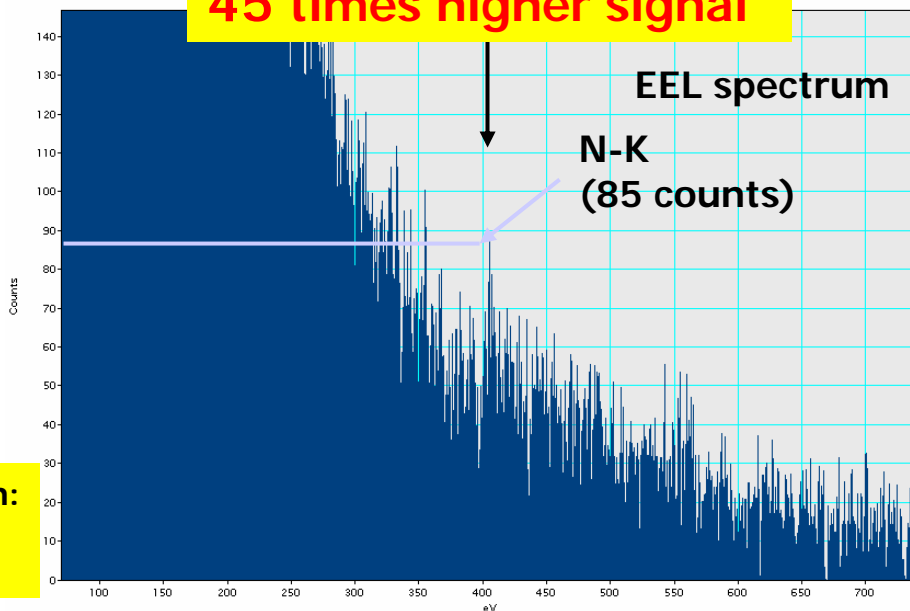
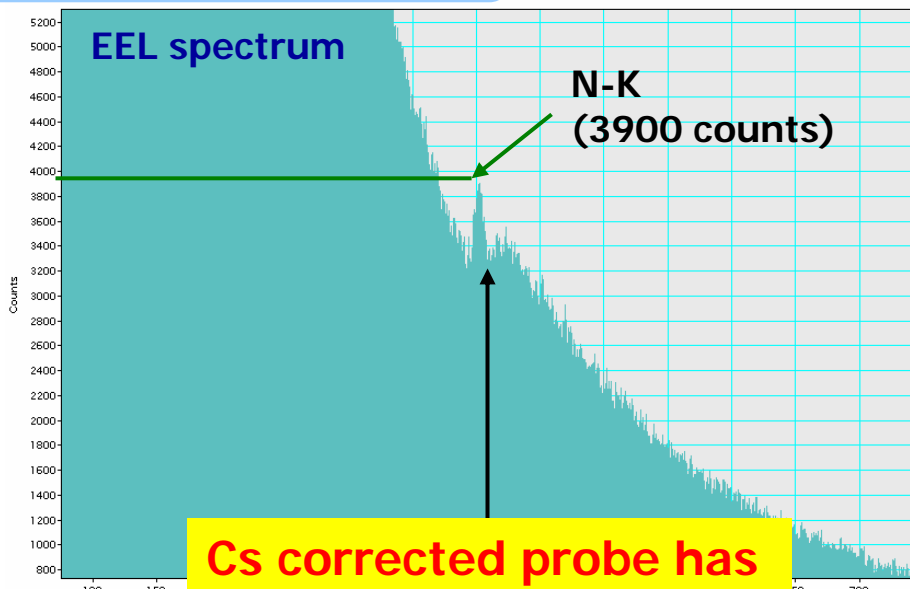


0.5 nm probe

EELS Spectrum from 1 pixel

$\text{Si}_x\text{N}_y$  area

Acquisition condition:  
0.5 nm probe  
0.001 sec / pixel

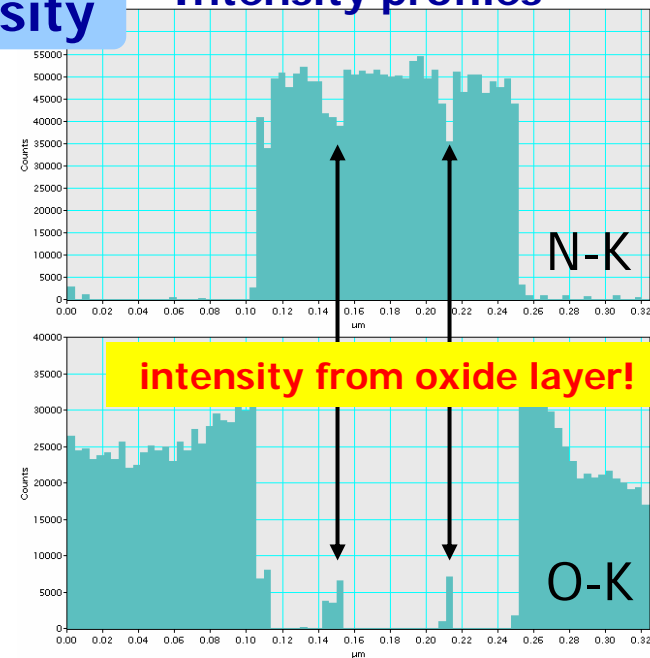
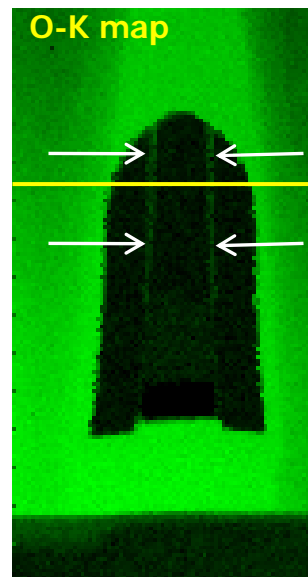
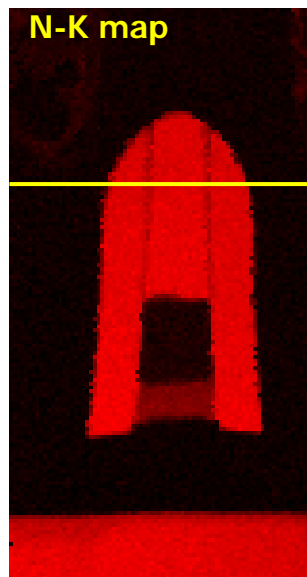
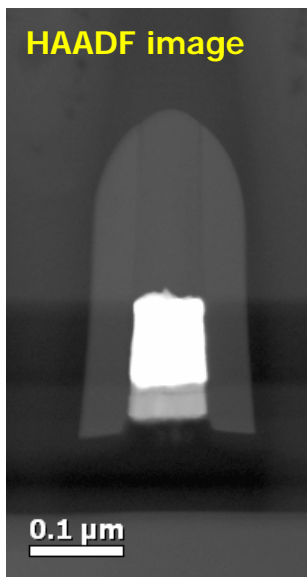




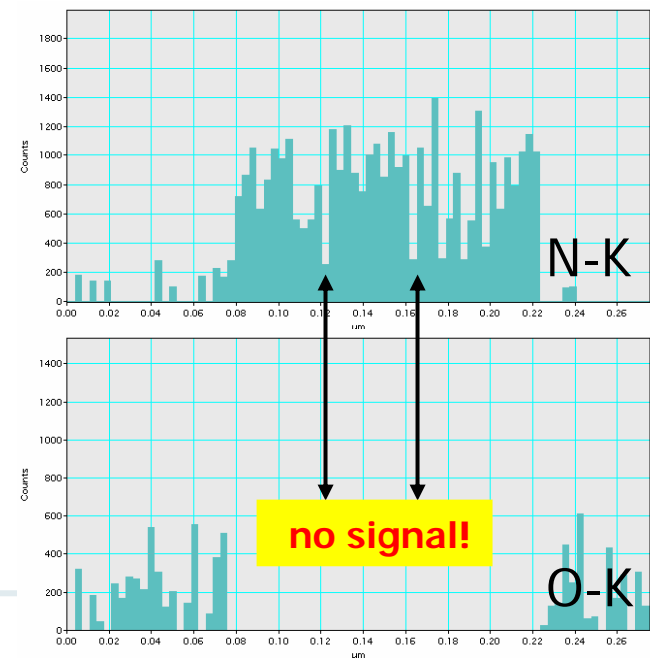
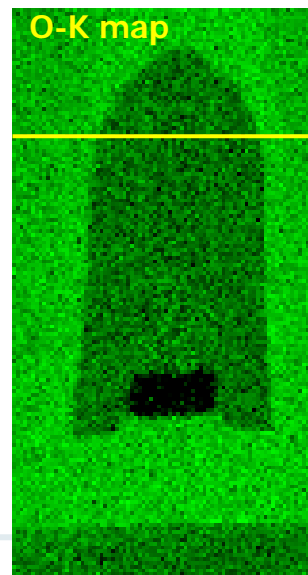
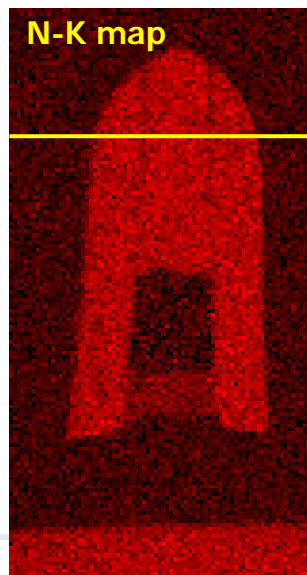
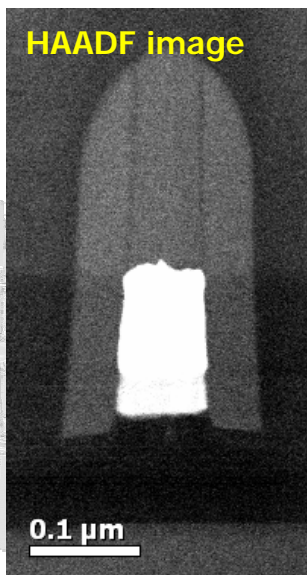
## Comparison of EELS mapping signal intensity

## Intensity profiles

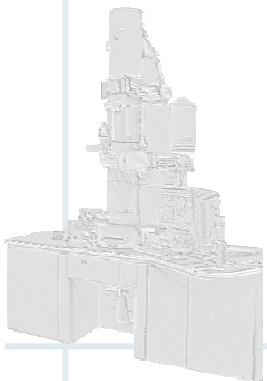
With Cs corrected



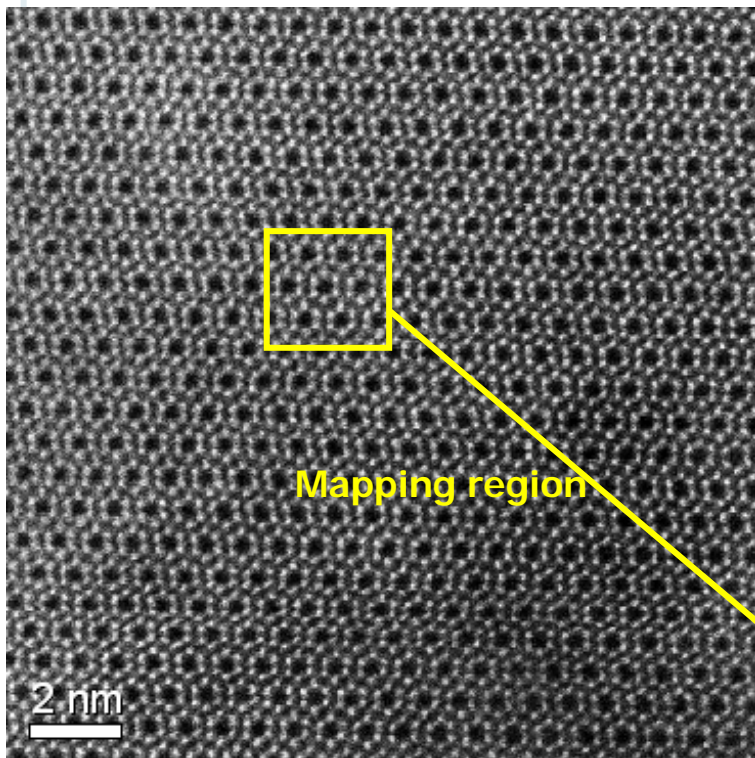
Without Cs corrected



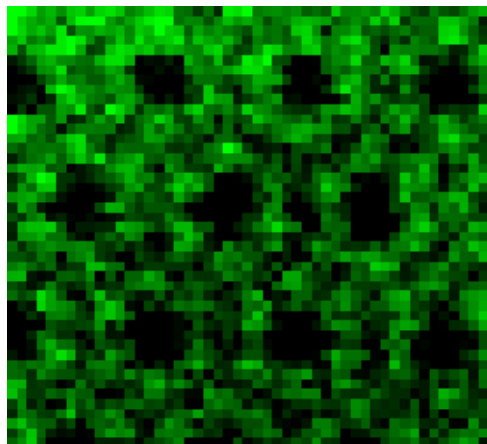
# Atomic level analysis capability of Cs corrected STEM (Atomic column by column mapping)



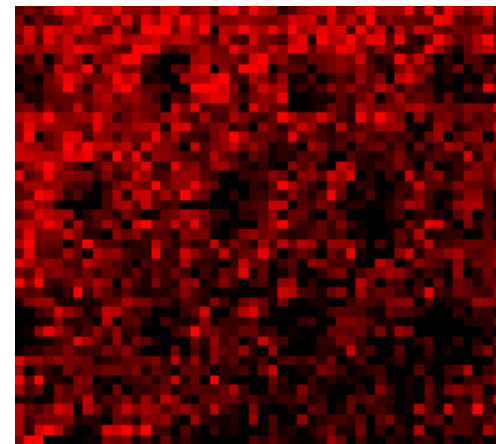
# Atomic column by column EELS mapping of Si<sub>3</sub>N<sub>4</sub>



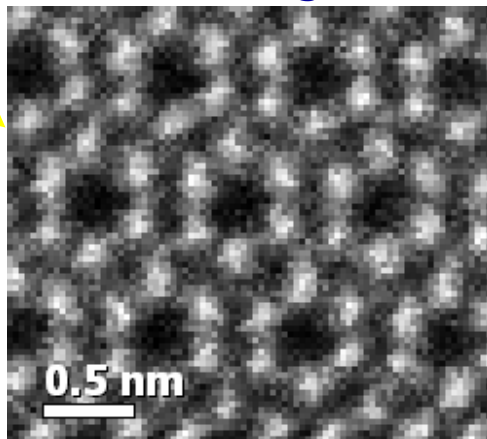
Si-L



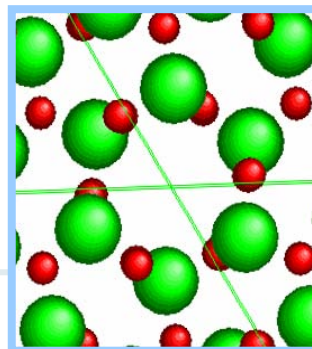
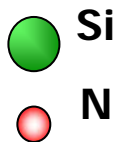
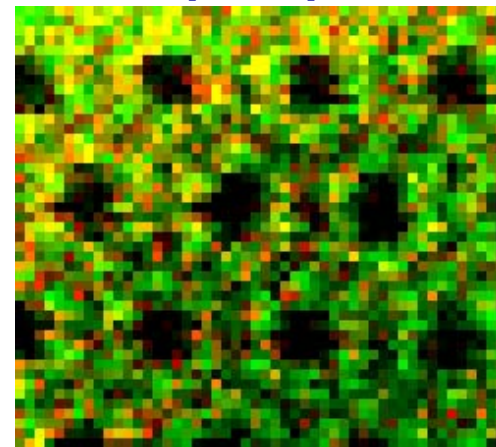
N-K



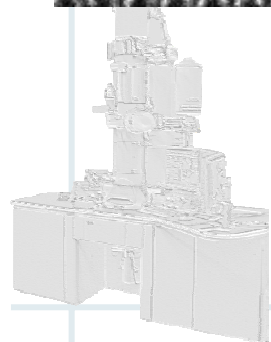
HAADF image



Overlap map

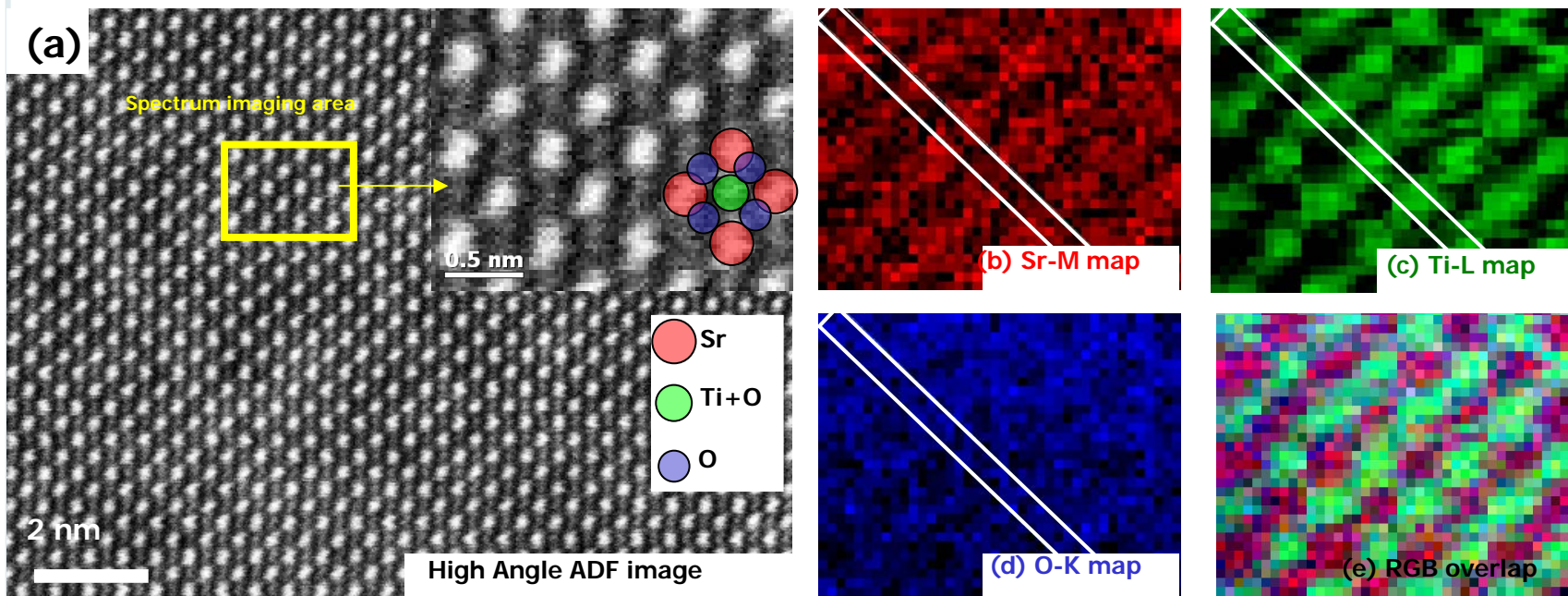


**Atomic resolution maps are obtained !**

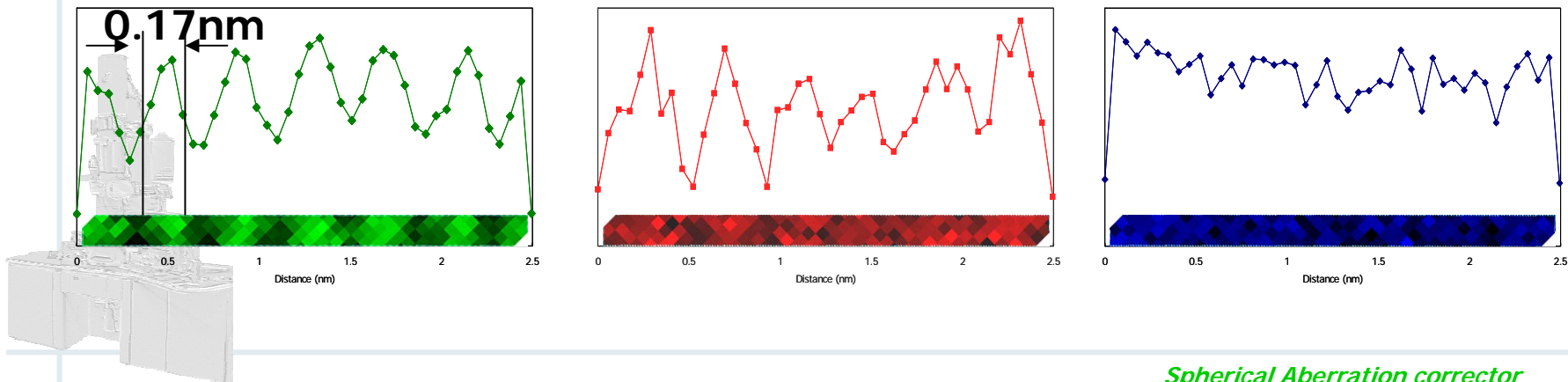




# Atomic column by column EELS mapping of SrTiO<sub>3</sub>



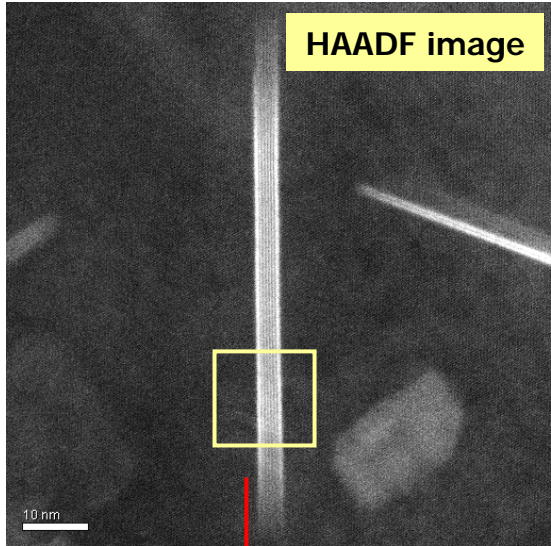
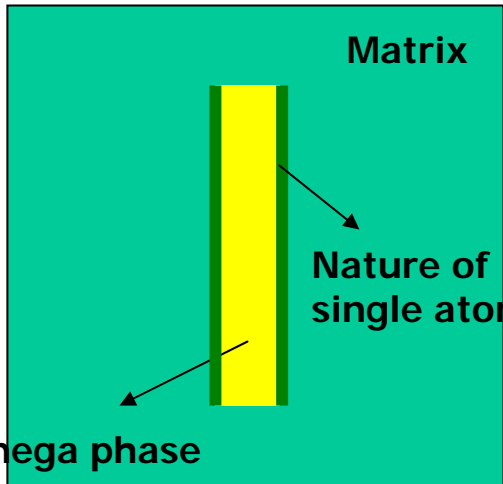
## Intensity profiles from white rectangle area in EELS map



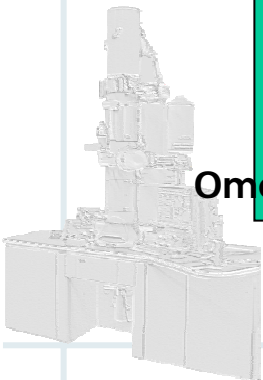
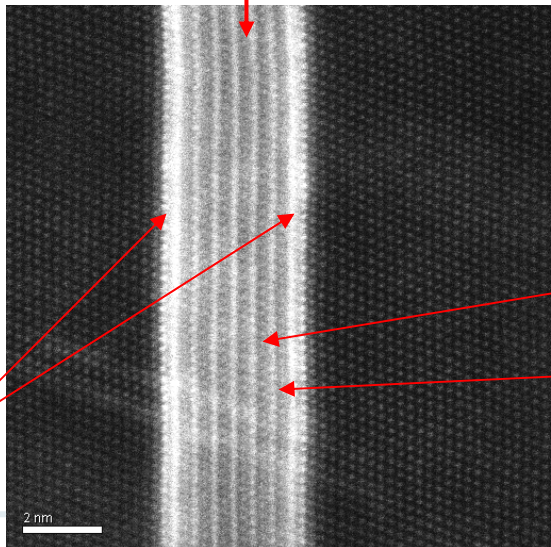
# High-Resolution High Speed Mapping by EDS of omega phase in Al-Cu alloy

Mg and Ag contained Al-Cu alloy has precipitates called omega phase (structure is  $\text{Cu}_2\text{Al}$ ).

What is the nature of the atomic layers between matrix and omega phase?



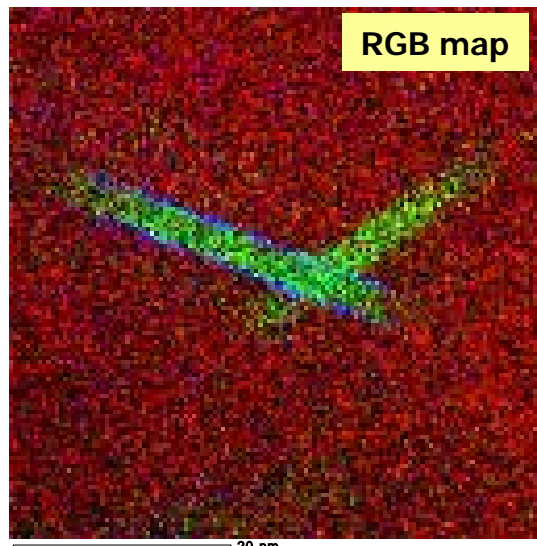
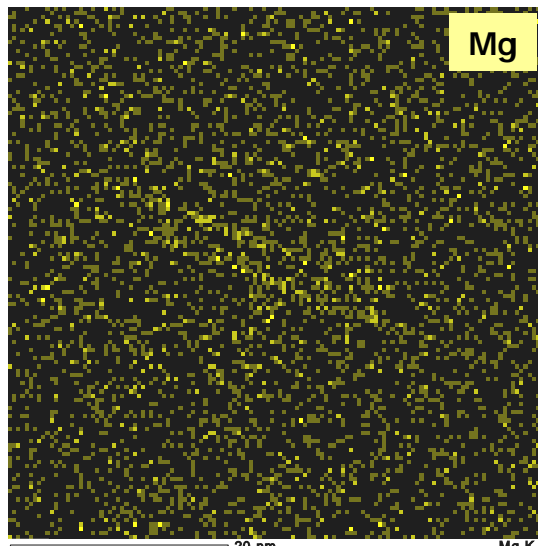
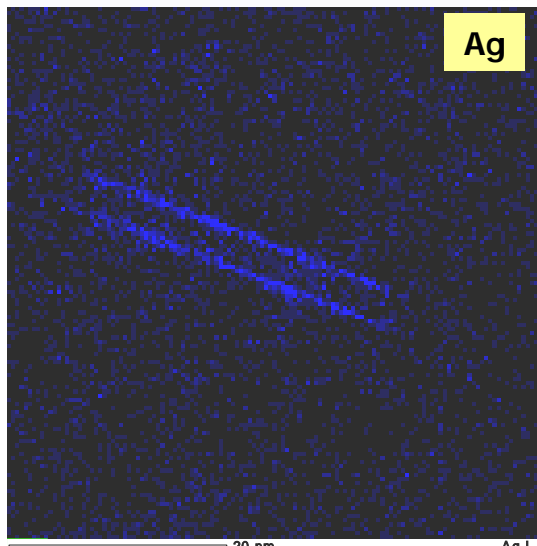
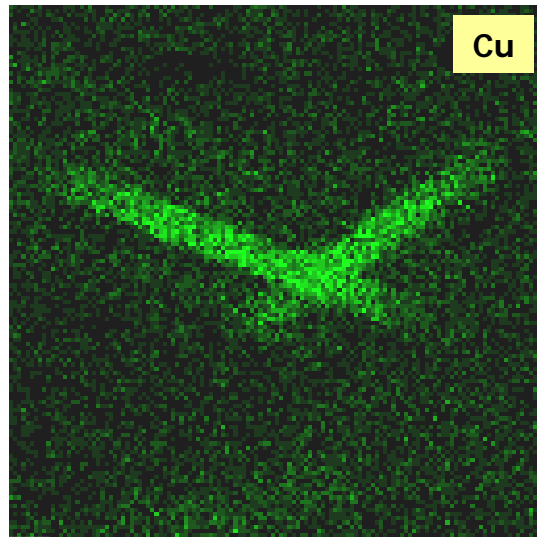
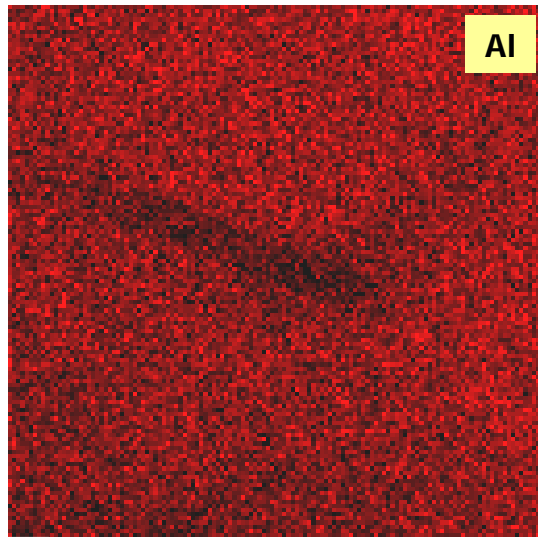
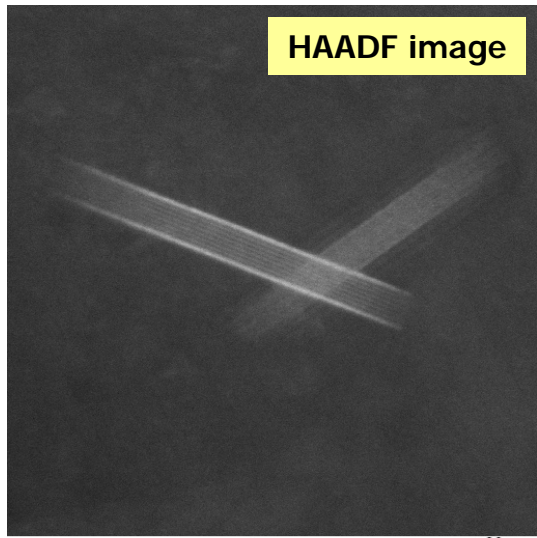
EDS mapping



erration corrector

for  
Probe forming Lens



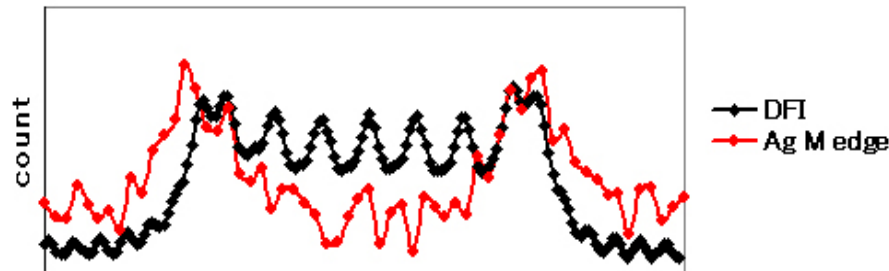
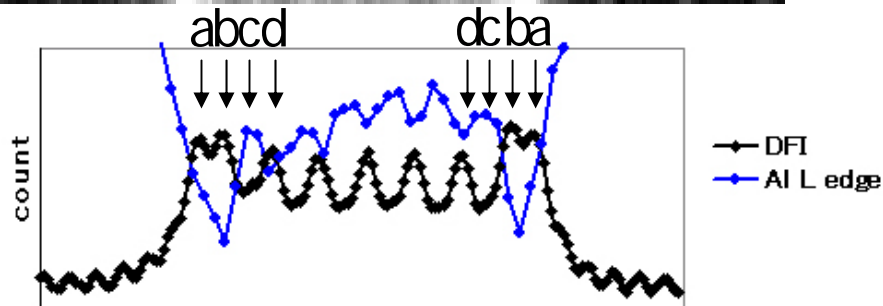
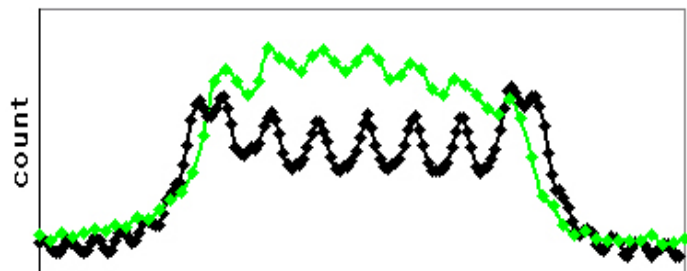
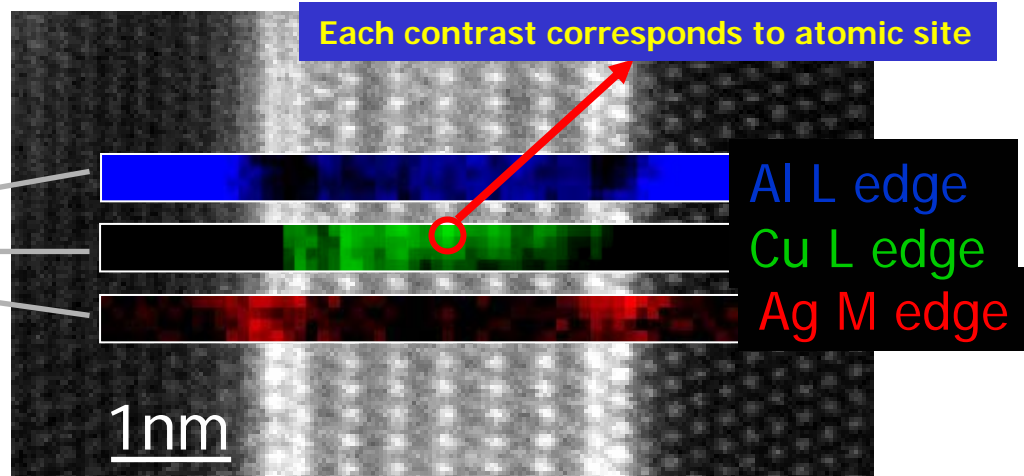
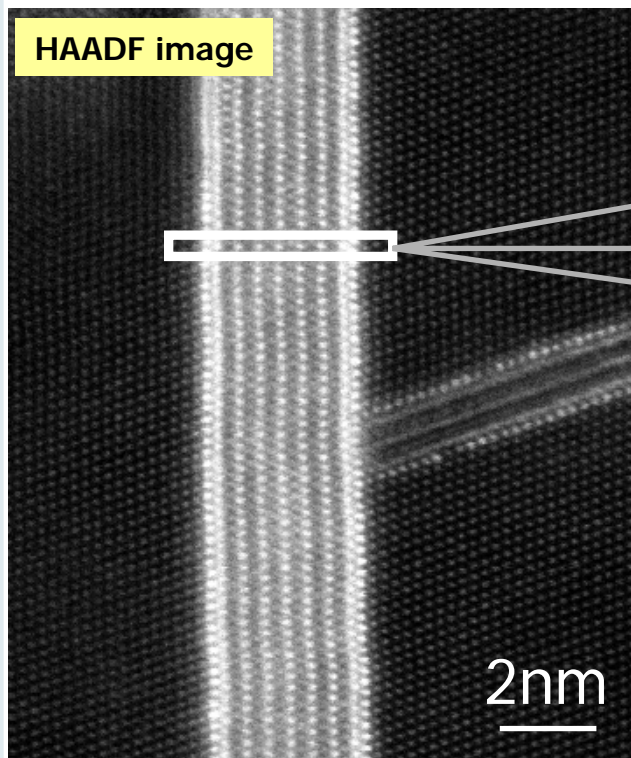


Measurement condition  
Pixel number 128x128pixel  
Frame number 0.5msec x 150 times  
Total time : 20 min  
Probe size 0.13 nm  
Magnification M

Ag and Mg layer can be visualized in only 20 min!



# Atomic resolution EELS mapping



Spherical Aberration corrector



for  
 Probe forming Lens



Serving Advanced Technology

# To conclude

## Cs corrected STEM :

- higher resolution imaging in BF and HAADF modes
- high throughput elemental/chemical analysis (EDS, EELS)
- atomic scale elemental/chemical analysis (EDS, EELS)
- accessible and robust tool for materials R&D (alloys, ceramics, interfaces, ...)

